Epi/MatPar User Guide

April 2008

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About this manual

This user guide describes two new utilities, Epi and MatPar, and how they are integrated into the TCAD Sentaurus tool suite. Both Epi and MatPar, with other TCAD tools, are useful for simulating compound semiconductor devices based on epitaxial multilayer stacks. Such structures are typically grown using epitaxial growth techniques such as metal-organic chemical vapor deposition or molecular beam epitaxy. Both Epi and MatPar facilitate structure generation and material parameter file handling for epitaxial multilayer stacks.

A typical epitaxial structure consists of multiple layers. The approach to structure generation by Sentaurus Structure Editor is to use several Scheme commands to generate each layer, to dope each layer, and to perform mesh refinement repeatedly. Epi avoids this: From a description of the structure in a comma-separated value (CSV) file, Epi automatically generates the required Scheme commands.

The approach for handling material parameters of ternary and quaternary materials in Sentaurus Device involves using a piecewise cubic spline interpolation scheme. The material parameters for ternaries and quaternaries depend on the x- and y-mole fractions, and are expressed as analytic equations in the literature. To create parameter files using these equations, the equations must be converted to a piecewise cubic spline format. Better handling of these parameters is obtained by directly using the analytic equations to compute the material parameters. This is accomplished using MatPar.

The Material Parameter Framework is a tool command language (Tcl)—based framework that efficiently implements new models for all of the material properties. The new models are implemented in terms of the built-in default models of Sentaurus Device. Using these models, MatPar can easily create customized material parameter files.

There is no unique set of material parameters for any particular property of a particular compound semiconductor. Typically, you would perform an extensive literature survey to obtain information about the material parameters for compounds. The Material Parameter Database provides a collection of material parameter values for several materials. It has been implemented so that it can also be used to visualize the variation of material properties as a function of doping concentration, mole fraction, and temperature using the Material Parameter Plotter.

Features of Epi

With Sentaurus Structure Editor, Epi can create epitaxial multilayer stacks. Process simulation is not involved in structure creation. Epi has the following features:

- The properties of the multilayer stack are specified in a CSV file that can be easily edited, for example, in a spreadsheet application. Epi uses this information to automatically generate a Scheme script file that contains the necessary commands for generating the structure using Sentaurus Mesh. This saves effort in creating the Scheme script file for Sentaurus Structure Editor.
- Sentaurus Structure Editor creates the complete device structure by processing the multilayer stack created by Epi. Additional processing steps such as patterning, layer deposition, and contact definitions can be implemented.
- Both two-dimensional and three-dimensional multilayer stacks can be created.
- The epitaxial layers can have constant or graded doping and mole-fraction profiles.
- The source parameter files used to generate user-defined material parameter files for use in Sentaurus Device are specified in the CSV file. Both regionwise and materialwise parameter files can be generated.
- Mesh refinement strategy can be specified in the CSV file.
- The extension column in the CSV file can contain arbitrary text. The column content can be written automatically into the Sentaurus Device command file. This is useful for inserting the same regionwise Physics statements for several regions in a multiple quantum-well structure.

Features of MatPar

MatPar extends the capabilities of Sentaurus Device by providing a framework for implementing user-defined models and creating user-defined material parameter files using these models. MatPar has the following features:

- It consists of the Material Parameter Framework, Material Parameter Database, and Material Parameter Plotter.
- The Material Parameter Framework is a general Tcl-based framework for implementing user-defined models and creating user-defined material parameter files.
- Using this framework, material property dependencies on physical variables such as temperature, doping, mole fraction, and wavelength can be easily defined using Tcl expressions. Equation-based and table-based models can be implemented.
- The Material Parameter Database is a collection of material property models and model parameter values for several compound semiconductor materials. It consists of Sentaurus Device models with Sentaurus Device default parameter values as well as new models.

- For each of the implemented models, parameter sets from different references from the literature have been implemented. The Material Parameter Database provides good initial parameter values that may serve as a baseline for custom calibrations.
- The Material Parameter Database is open and extensible. The model files are Tcl script files. You can read the model files and modify the files. These can be used as template files for implementing new models or different model parameter sets for existing models.
- The Material Parameter Plotter, which is an Inspect-based utility, visualizes the variation of material properties as a function of doping, temperature, mole fraction, wavelength, and so on. It can also be used to compare a particular material property value for different models in the Material Parameter Database.

Typographic conventions

Convention	Explanation	
Blue text	Identifies a cross-reference (only on the screen).	
Bold text	Identifies a selectable icon, button, menu, or tab. It also indicates the name of a field, window, dialog box, or panel.	
Courier font	Identifies text that is displayed on the screen or that the user must type. It identifies the names of files, directories, paths, parameters, keywords, and variables.	
Italicized text	Used for emphasis, the titles of books and journals, and non-English words. It also identifies components of an equation or a formula, a placeholder, or an identifier.	
Key+Key	Indicates keyboard actions, for example, Ctrl+I (press the I key while pressing the Control key).	
Menu > Command	Indicates a menu command, for example, File > New (from the File menu, select New).	
NOTE	Identifies important information.	

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About this manual

Contacting your local TCAD Support Team directly

CHAPTER 1 Simulation tool flow

This chapter describes the simulation tool flow using Epi and MatPar.

Project directory structure

Epi and MatPar are distributed as part of a special Sentaurus Workbench project called the Epi/MatPar project. The Sentaurus Workbench directory name for this project is epi. The Epi/MatPar project consists of:

- Epi, creates the multilayer stack.
- Sentaurus Structure Editor, which performs further device processing on the multilayer stack, adds contacts, and creates the complete device for device simulation.
- MatPar, which creates the main parameter file and user-defined parameter files.

The project (epi) is contained in the parent directory epi_template, which is referred to as the Epi/MatPar template directory. As summarized in Table 1, epi_template also contains the subdirectories lib, par, and pardb. The epi_template directory serves as a template for creating customized applications that use Epi and MatPar (see Chapter 5 on page 85).

Table 1 Subdirectories in template directory, all paths are relative to epi_template

Subdirectory	Description
epi	Subdirectory name of the Epi/MatPar project, containing input and output files.
epi/npar	Subdirectory containing user-defined parameter files created by MatPar. NOTE The location for storing the user-defined parameter files cannot be changed.
lib	Subdirectory containing source files and library files for Epi and MatPar. The library files contain helper procedures. Some files are part of the Material Parameter Framework.
par	Subdirectory containing user-specified source parameter files, which are part of the Material Parameter Framework.
pardb	Directory name of Material Parameter Database, containing model files.
pardb/mprPlotter	Directory name of Material Parameter Plotter.

The Epi/MatPar template project is distributed as part of the application note *Template for Creating and Simulating Multilayered Heterostructure Devices with TCAD Sentaurus* [1].

Files in template directory

Table 2 summarizes all of the files specific to the epi_template directory. The files are divided into three categories:

- Tool-specific internal files: These contain tool-specific source code and utility functions. Internal files for both Epi and MatPar are located in the lib subdirectory. It is not recommended that users modify these files.
- Tool input files: These are user-supplied input command files for Epi and MatPar. Most are in the epi subdirectory. The source parameter files are located in the par subdirectory.
- Tool output files: These are output files created by the tools. Most are in the epi subdirectory. The user-defined material parameter files created by MatPar are in the epi/npar subdirectory.

In Table 2, if a file is listed as epi/epi_epi.csv, the location of this file is epi_template/epi/epi epi.csv.

In addition, n@node@ is replaced by nX in the file names. For example, the file n@node@_epi.scm is listed as nX_epi.scm for brevity.

Table 2 Files in subdirectories of template directory

File type	File	Description	
	epi/gtooldb.tcl	Contains commands that add Epi and MatPar to a Sentaurus Workbench project.	
Epi			
Internal	lib/epi.gif	Image file for Epi icon.	
	lib/epi.tcl	Tcl source code for Epi.	
	lib/helper.tcl	Contains helper procedures for Epi and MatPar.	
	lib/layers.tcl	Contains additional procedures to create multilayer stacks.	
Input	epi/epi_epi.csv	User-specified CSV file, containing all relevant data for each layer of the multilayer stack.	
		Contains AxisAligned section [2] of Sentaurus Mesh command file. Created only if (yref qw) is used in the Refinement field of the Epi command file.	
	epi/nX_epi.scm	Contains Scheme commands to create multilayer stack and to perform mesh refinement.	
	epi/nX_epi.tcl	Contains information about each layer in the form of Tcl variables.	
	epi/nX_epi_gen.scm	Uses nX_epi.scm to create the input files, nX_epi_msh.bnd and nX_epi_msh.cmd, for the mesher.	

Table 2 Files in subdirectories of template directory

File type	File	Description	
Output	epi/nX_epi_msh.bnd	Input boundary file for the mesher.	
	epi/nX_epi_msh.cmd	Input command file for the mesher.	
	epi/nX_epi_msh.tdr	Multilayer stack created by Epi. Used only to view and verify the multilayer stack.	
Sentaurus	Structure Editor		
Input	epi/sde_dvs.cmd	User-specified command file that is used to generate the complete device from the multilayer stack. Contains commands for performing additional device-processing steps on the multilayer stack and for adding contacts.	
Output	epi/nX_msh.bnd	Input boundary file for Sentaurus Mesh.	
	epi/nX_msh.cmd	Input command file for Sentaurus Mesh.	
	epi/nX_msh.tdr	Complete device structure. Used for device simulation.	
MatPar			
Internal	lib/compound_lib.tcl	Contains procedures for interpolating property values for compound semiconductors.	
	lib/helper.tcl	Contains helper procedures for Epi and MatPar.	
	lib/MakeParDoc.tcl	Tcl script file for creating online HTML documentation of Material Parameter Database.	
	lib/mpr.gif	Image file for MatPar icon.	
	lib/mpr.tcl	Tcl source file for MatPar.	
	lib/ PhysicalConstants.tcl	Contains definitions of fundamental physical constants and user- defined constants. Used by model files to calculate model parameters and material properties.	
	lib/printPar.tcl	Contains procedures for printing the parameter sections in user-defined parameter files.	
Input	epi/MatPar_mpr.cmd	User-specified command file for MatPar. Used to define some variables and invoke some procedures.	
	par/ <material>.par</material>	User-specified source parameter file. There is one <material>.par file for each material or region. MatPar does not process this file, and it is included as is, in the user-defined parameter file. Use this file if Tcl procedures are not needed.</material>	
	par/ <material>.tcl</material>	User-specified Tcl source parameter file. There is one <material>.tcl file for each material or region. You specify the material property models in this file, and MatPar processes it to create user-defined parameter files.</material>	

Table 2 Files in subdirectories of template directory

File type	File	Description
Input	par/ material_template.tcl	A template Tcl source parameter file. Useful for creating the Tcl source parameter file for any material.
	pardb// <model>.tcl</model>	Model files. Material parameter calculations are implemented in model files. All model files are in an appropriate directory under pardb.
		The main parameter file required by Sentaurus Device. The name of this file can be specified by the user in the MatPar command file.
	epi/npar/ <parfilemask>.par</parfilemask>	User-defined parameter files created by MatPar. The name of regionwise files depends on the value of parFileMask defined in epi_epi.csv. The name of materialwise files is n (node) _ (material) .par.

NOTE In the context of Table 2 on page 2 and Figure 1 on page 5, nx is part of the file name of the output files of both Epi and MatPar. In general, in this manual, nx is part of the file name of the output file of any TCAD Sentaurus tool.

Typical device simulation tool flow

Figure 1 shows a device simulation tool flow. It starts with Epi, which generates the multilayer stack. Sentaurus Structure Editor creates the complete device structure (the multilayer stack with contacts). MatPar creates the user-defined material parameter files, which are used by Sentaurus Device to simulate the electrical/optical characteristics of the device. Finally, Tecplot SV is used to visualize the output from the simulation in 2D and 3D, and Inspect plots the electrical characteristics (not shown in Figure 1).

Epi creates a multilayer stack with the help of Sentaurus Structure Editor and Sentaurus Mesh, which is not explicitly included in the Sentaurus Workbench tool flow. Instead, Sentaurus Mesh is called from Sentaurus Structure Editor internally. The input file for Epi, epi epi.csv, contains information about each layer as well as the entire structure. It also contains information about the source parameter files (<material>.tcl or <material>.par) to be used by MatPar to generate user-defined material parameter files.

Epi generates Scheme script files, n@node@ epi.scm and n@node@ epi gen.scm, and a Tcl script file, n@node@ epi.tcl. Epi internally invokes Sentaurus Structure Editor and the mesher to create the multilayer stack and to store the structure in n@node@ epi msh.tdr as follows.

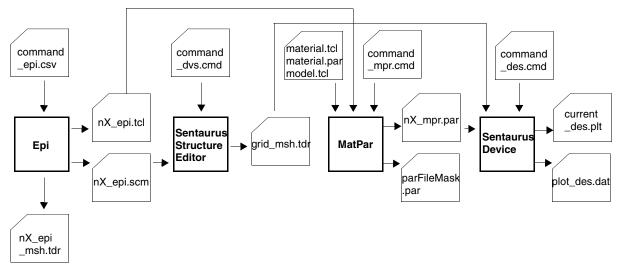


Figure 1 Device simulation tool flow in Sentaurus Workbench that includes Epi, Sentaurus Structure Editor, MatPar, and Sentaurus Device

The file n@node@_epi.scm contains commands for creating the multilayer stack and for mesh refinement in the y-direction, and it is sourced inside n@node@_epi_gen.scm, which is used by Sentaurus Structure Editor to generate the input files of the mesher, n@node@_epi_msh.bnd and n@node@_epi_msh.cmd. Finally, Sentaurus Mesh creates the multilayer stack in the file n@node@_epi_msh.tdr. The TDR file created at this stage can be used to verify the multilayer stack.

All Scheme variables from n@node@_epi.scm and complete information about all of the layers in the structure and the source material parameter files are stored in n@node@_epi.tcl as Tcl variables.

The Scheme script file n@node@_epi.scm is sourced in the command file sde_dvs.cmd for the subsequent Sentaurus Structure Editor instance to create the complete device structure. In this instance of Sentaurus Structure Editor, additional device-processing steps, such as etching of layers and deposition of additional layers, can be performed. This is followed by the addition of contacts and mesh refinement. Finally, the device structure is generated using Sentaurus Mesh and is stored in n@node@_msh.tdr.

Sentaurus Device needs a main parameter file that contains a list of references to the user-defined regionwise and materialwise parameter files. MatPar creates these parameter files. The layer information is loaded into MatPar by sourcing n@node@_epi.tcl in the MatPar command file MatPar_mpr.cmd. The models are specified for each material in the Tcl source parameter file (<material>.tcl) for each material. The models and the model parameters are implemented in the model files (<model>.tcl) in the Material Parameter Database.

1: Simulation tool flow

File references: @file_type@

MatPar uses all of these input files to create the main parameter file, n@node@_mpr.par, as well as the user-defined parameter files. The user-defined parameter files are stored in the epi/npar subdirectory.

File references: @file_type@

Table 3 lists some of the file references @file type@ defined in the file gtooldb.tcl.

Table 3 Description of file references defined in gtooldb.tcl

File reference	File name
@episcm@	epi/nX_epi.scm
@epitcl@	epi/nX_epi.tcl
@mprpar@	epi/nX_mpr.par
@tdr@	epi/nX_msh.tdr (electrical grid)
@tdrop@	epi/nX_op_msh.tdr (optical grid; useful for dual-grid simulation)

References

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- [1] Template for Creating and Simulating Multilayered Heterostructure Devices with TCAD Sentaurus, TCAD Sentaurus application note, available from SolvNet at https:\\solvnet.synopsys.com, April 2008.
- [2] *Mesh Generation Tools User Guide*, Version A-2007.12, Mountain View, California: Synopsys, Inc., 2007.

CHAPTER 2 Using Epi

This chapter describes how to use Epi to create a multilayer stack.

Overview

Epi creates a multilayer stack from the user-specified description of the stack in the Epi command file epi epi.csv.

Figure 2 shows an example of a multilayer stack created by Epi. The structure is described in terms of the:

- Geometric properties of the complete multilayer stack (see Global section on page 9).
- Properties of each layer (see Layers section on page 13).
- Mesh refinement strategy (see Layers section on page 13).
- Mesh generation and the options for invoking the meshing engine (see Mesh refinement strategy on page 18).
- Names of the Extension columns (see Extension columns on page 31).

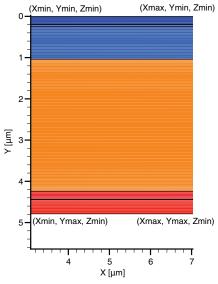


Figure 2 Epi-generated multilayer stack with the coordinate system; positive z-direction points into the plane of the paper

Epi uses the structure information to generate automatically a Scheme script file (n@node@_epi.scm). This file contains commands to generate the structure using Sentaurus Mesh (n@node@_epi_msh.tdr). This saves effort in creating the Scheme script file. Epi also generates a Tcl script file, n@node@_epi.tcl, which contains Tcl variables that store all of the information from the CSV file.

In addition to this information, the following MatPar-specific information is specified in the CSV file (see Layers section on page 13):

- Source material parameter files used by MatPar to create the user-defined material parameter files.
- Regionwise statements inserted by MatPar into the preprocessed Sentaurus Device command file.

Starting Epi

The Epi source file is the Tcl script file, epi.tcl, which is located in the lib subdirectory. The Tcl interpreter gtclsh executes Epi. gtclsh is a Tcl shell that has been extended with all of the internal commands of the Sentaurus Workbench framework [1].

You can start Epi from either the command line or Sentaurus Workbench.

Epi is driven by the command file epi_epi.csv. Epi can be invoked from the command line by executing the following command from inside the epi subdirectory:

```
gtclsh ../lib/epi.tcl <command_file>
```

The file gtooldb.tcl contains appropriate commands to launch Epi automatically through the Scheduler when working inside Sentaurus Workbench.

The Epi command file <code>epi_epi.csv</code> can be easily edited in either a text editor or a spreadsheet application. The CSV file can be directly accessed from Sentaurus Workbench by using one of the following methods:

- To open the file in SEdit, right-click the Epi icon in the tool row, and select Edit Input > Commands.
- To open the file in a spreadsheet application, for example, OpenOffice on Linux, right-click the Epi icon and select **Edit Input** > **Edit in Spreadsheet Application**.

NOTE If epi_epi.csv is opened in a spreadsheet application, the file must be saved in the CSV format.

Saving command file in CSV format in OpenOffice

To save the command file in OpenOffice, in the CSV format:

- 1. File > Save As.
- 2. In the **File Selection** dialog box:
 - a) Select **Text CSV** (.csv;.txt) as the file name extension.
 - b) Select Edit filter settings.
 - c) Click Save.
- 3. In the Overwrite file? dialog box, select Yes.
- 4. In the **Export of text files** dialog box:
 - a) Select "," as the field delimiter.
 - b) Leave the **Text delimiter** field empty.
- 5. Click OK.

Epi command file

The Epi command file epi_epi.csv contains all of the information needed to create the multilayer stack and consists of the:

- Global section, which contains variable definitions related to the complete multilayer stack.
- Layers section, which defines layer properties and source parameter files for user-defined regionwise parameter files.
- Material and Interface section, which defines source parameter files for user-defined materialwise parameter files and materialwise interface parameter files.

Global section

The Global section defines variables called Epi variables, which define the properties of the complete multilayer stack. The value of a particular Epi variable is the same for all layers in the stack. The following types of Epi variable can be defined:

- *Predefined Epi variables* are predefined by Epi and have default values. You can modify the value of these variables. Table 4 on page 11 describes these variables.
- *User-defined Epi variables* are defined by the user.

2: Using Epi

Epi command file

All Epi variables are available to Sentaurus Structure Editor in the subsequent node as Scheme variables (through n@node@_epi.scm), as well as to MatPar (through n@node@_epi.tcl) as Tcl variables.

All statements in the Global section begin with one of the following two characters:

- The hash (#) is used to insert comments into the CSV file or to add Sentaurus Workbench preprocessor #-commands [1].
- The dollar sign (\$) precedes the global command and the extended commands repeat, end, and i (see Extended commands on page 31).

The global command is used either to modify the predefined Epi variables or to create user-defined Epi variables. The following syntax is used:

```
$global variable1=<value>, variable2=<value>, ...
```

An example of a typical Global section is:

```
# Simple solar cell structure
$global Ytop=0.0
$global Xmin=0.0, Xmax=@wtot@
$global wtot=@wtot@
$global dXmin=5, dXmax=5, dYmin=0.5, dYmax=0.5
$global generate=tdr
$global parFileMask=./npar/n(node)_(material)_(doping).par
$global append columnNames extension
```

where:

- Ytop, Xmin, and dXmin are predefined Epi variables.
- @wtot@ is a Sentaurus Workbench variable.
- wtot is a user-defined Epi variable.

As this example shows, Sentaurus Workbench variables can also be accessed in the CSV file.

Table 4 Structure information in Global section of CSV file, listing predefined Epi variables

Structure information	Predefined Epi variables	Description	Default value	Unit
Geometric prop	erties of complete	e multilayer stack in all three directions	-	
Structure	Ytop	The y-coordinate of the top edge of the top layer.	0	μm
thickness	Ybot	The y-coordinate of the bottom edge of the bottom layer. NOTE Calculated by Epi. Do not define this variable.	_	μm
		Ybot - Ytop = structure thickness. There is no default value for structure thickness since Epi calculates it.		
Structure width	Xmin	Leftmost extent of the multilayer stack.	0	μm
	Xmax	Rightmost extent of the multilayer stack.	1	μm
		$xmax - xmin = structure width.$ The default value of structure width is 1 μm .		
Structure depth	Zmin	Frontmost extent of the multilayer stack.	0	μm
	Zmax	Rearmost extent of the multilayer stack.	0	μm
		$\label{eq:max-Zmin} \begin{split} & Z\text{max} - Z\text{min} = \text{structure depth.} \\ & \text{The default value of structure depth is } 0 \ \mu\text{m} \ . \\ & \text{NOTE If } Z\text{max} - Z\text{min} = 0 \text{, a 2D structure is generated.} \end{split}$ structure is generated.		
Global mesh re	finement strategy	for entire structure	•	•
Minimum element size	dXmin, dYmin, dZmin	Minimum background element size in the x-, y-, and z-direction.	9999.0	μm
Maximum element size	dXmax, dYmax, dZmax	Maximum background element size in the x-, y-, and z-direction.	9999.0	μm
Electrode inform	mation			
Top contact	topContact	If defined, places a contact on the top of the multilayer stack.	_	_
Bottom contact	bottomContact	If defined, places a contact at the bottom of the multilayer stack.	_	-
Mesher informa	tion			•
Tool name	mesher	Specifies the name of the meshing tool: <snmesh mesh>.</snmesh mesh>	snmesh	_
Tool options	meshOptions	Optional commands for the mesher.	_	-
	1	1	1	

Table 4 Structure information in Global section of CSV file, listing predefined Epi variables

Structure information	Predefined Epi variables	Description	Default value	Unit
Structure file	generate	Specifies the format of the structure file (n@node@_epi_msh) used to store the multilayer stack created by Epi: <tdr grd="" ="">. If generate is not specified, the file is not created.</tdr>	-	_
Information use	ed by MatPar			
Parameter file name	parFileMask	Determines the file name of the user-defined parameter files. In general: parFileMask=./npar/n(node)_(material) _(doping)_(xMole)_(yMole).par	Regionwise files: ./npar/n(node) _(material)_ (xMole).par Materialwise files: ./npar/n(node) _(material).par	_
Extension column names	_	A command is used to add extension columns: \$global append columnNames <column1> <column2></column2></column1>	_	_

Extent of structure

The variables Xmin, Xmax, Ytop, Ybot, Zmin, and Zmax describe the extent of the multilayer stack in all three directions. Figure 2 on page 7 illustrates the coordinate system. The positive z-axis points into the plane of the paper. Epi creates the multilayer stack with increasing y-coordinate as the growth direction. The coordinates of the starting point are defined by Xmin, Ytop, and Zmin.

By default, Xmin = Ytop = Zmin = 0. In addition, as shown in Figure 2, Xmin < Xmax, Ytop < Ybot, and Zmin < Zmax. All layers have the same width and depth, which can be defined using Xmin, Xmax, Zmin, and Zmax (see Table 4 on page 11).

Ytop can be redefined, whereas Ybot is calculated from the thickness of each layer in the structure. Epi decides the dimensionality of the structure using the values of Zmin and Zmax (see Table 4).

Global mesh refinement strategy

dXmin and dXmax are minimum and maximum element sizes, respectively, for global mesh refinement in the x-direction for the entire structure. dYmin, dYmax, dZmin, and dZmax have similar meaning.

NOTE Epi generates global refinement commands only if the value of at least one of these variables is modified by the user.

If you define dXmin=0, or dYmin=0, or dZmin=0, Epi resets this minimum element size to be equal to the corresponding maximum element size. The global refinement window is positioned to cover the complete multilayer stack.

NOTE Epi saves the structure in a TDR file (n@node@_epi_msh) only if you define the generate variable. In addition, this TDR file is used only for verifying the multilayer stack.

NOTE For details on parFileMask, see Material and Interface section on page 19.

Layers section

All layers of the multilayer stack are defined in the Layers section, which consists of one statement for each layer to be created, starting with the top layer of the structure. The layer description in each statement consists of several comma-separated fields:

```
<Region>, <Material>, <SourceParFile>, <Thickness>, <Doping>, <MoleFraction>, <Refinement>, <Extension>
```

The fields contain information about each layer that Epi uses to create the multilayer stack. Table 5 describes the fields of the Layers section.

Table 5 Fields in Layers section of CSV file

Field	Description	Unit
Region	Name of the region to be created.	-
Material	Material names that Sentaurus Device recognizes.	_
SourceParFile	Name of the source parameter file used to create the user-defined material parameter files. If the file extension is .tcl, it is processed. If the file extension is .par, it is included as is.	-
Thickness	Thickness of each layer. If this field is empty, the region is not created.	μm
Doping	Doping of each layer. It is specified using commands in Table 7 on page 16. A negative sign indicates p-type doping; a positive sign indicates n-type doping. Certain doping profiles can also be specified.	cm ⁻³
MoleFraction	Mole fraction for ternary or quaternary materials. It is specified using commands in Table 8 on page 18. Linear mole-fraction profiles can also be specified.	[1]

Epi command file

Table 5 Fields in Layers section of CSV file

Field	Description	Unit
Refinement	Regionwise mesh refinement strategy for each layer. It can be omitted if a global refinement strategy is defined in the Global section. It is specified using commands in Table 9 on page 18.	μm
Extension	This field is for arbitrary content. The column contents can be inserted into the preprocessed Sentaurus Device command file. Multiple Extension columns are allowed.	_

Table 6 shows an example of the content of the Layers section and Material and Interface section in tabular format. The corresponding listing in the CSV file is:

```
# Layers section
# Region, Material, SourceParFile, Thickness, Doping, MoleFraction,
# Refinement, Extension
cap, GaAs,, 0.5, -5.00e19,, (yref 0.1),
fsf, AlGaAs, AlGaAs.tcl, 0.03, -4.00e18, 0.8, (yref 0.01),
emitter, GaAs, GaAs.tcl, 0.5, -5.00e17, , (mbox 0.05 1.1
both) , Recombination (Radiative)
base, GaAs,, 2.5, 1.00e17,, (mbox 0.05 1.1 both), Recombination (Radiative)
substrate,Germanium,Ge.tcl,5.0,1.00e18,,(mbox 0.05 1.1 both),
# Material and Interface section
# Materialwise parameter file definition
,GaAs,GaAs.tcl,,1.00e18,,,
,MgF,MgF.par,,,,
# Materialwise interface parameter file definition
,GaAs/AlGaAs,GaAs_AlGaAs.par,,,
```

Table 6 Example of Layers and Material and Interface sections of epi_epi.csv

Region	Material	SourceParFile	Thickness	Doping	Mole Fraction	Refinement	Extension
# Layers se	# Layers section:						
сар	GaAs		0.5	-5.00e19		(yref 0.1)	
fsf	AlGaAs	AlGaAs.tcl	0.03	-4.00e18	0.8	(yref 0.01)	
emitter	GaAs	GaAs.tcl	0.5	-5.00e17		(mbox 0.05 1.1 both)	Recombination (Radiative)
base	GaAs		2.5	1.00e17		(mbox 0.05 1.1 both)	Recombination (Radiative)
substrate	Germanium	Ge.tcl	5.0	1.00e18		(mbox 0.05 1.1 both)	

Table 6 Example of Layers and Material and Interface sections of epi epi.csv

Region	Material	SourceParFile	Thickness	Doping	Mole Fraction	Refinement	Extension
# Material a	and Interface se	ction:					
# Materialv	vise parameter f	ile definition					
	GaAs	GaAs.tcl		1.00e18			
	MgF	MgF.par					
# Materialv	# Materialwise interface parameter file definition						
	GaAs/AlGaAs	GaAs_AlGaAs.par					

NOTE If all fields following a particular field are empty in a layer definition, the number of commas after this field is irrelevant. For example, all fields after Doping are empty for the materialwise parameter file definition of GaAs. Therefore, this can be written in one of two ways:

```
,GaAs,GaAs.tcl,,1.00e18,,,
,GaAs,GaAs.tcl,,1.00e18,
```

Region and material names

Epi creates a region for each layer. The name of the region is specified in the Region field. Epi uses the region name to create regionwise doping profiles, mole-fraction profiles, and mesh refinements. For each layer, the names of materials that Sentaurus Device recognizes are specified in the Material field. For example, for a germanium layer, Germanium is specified in the Material field instead of Ge.

To generate a list of all materials that Sentaurus Device recognizes, use:

```
sdevice -L:materials
```

Thickness

The thickness of each layer in micrometers is specified in the Thickness field. If the Thickness field is empty, Epi does not create the layer and, therefore, does not create the region.

Doping profiles

The doping information for each layer is specified in the Doping field. A constant doping concentration or a graded doping profile can be specified using the commands in Table 7. These commands create region-based doping profiles for the layer in the y-direction. The following types of doping profile can be defined in the y-direction:

- Linear function
- Error function
- Gaussian function

Table 7 Commands for Doping field

Command	Description				
<doping></doping>	Constant doping concentration.				
Linear function doping profile					
(lin <ntop> <nbot>)</nbot></ntop>	Linear region-based doping profile using analytic profile.				
Ntop	The value of doping concentration at the top edge of the layer [cm^{-3}].				
Nbot	The value of doping concentration at the bottom edge of the layer [cm^{-3}].				
(lin <ntop> <nbot>) (default <doping>)</doping></nbot></ntop>	Linear doping profile with a default reference doping concentration value of <doping>[cm⁻³].</doping>				
Error function or Gaussian function doping profile					
<pre>(<erf gauss="" =""> <nmax> <ymax> <length> <ue de="" ="">) (default <doping>)</doping></ue></length></ymax></nmax></erf></pre>	Error or Gaussian function doping profile with a default reference doping concentration value of <doping>[cm⁻³].</doping>				
Nmax	Maximum concentration/peak concentration [cm ⁻³].				
ymax	Symmetry position/peak position [µm].				
length	Length [µm].				
<ue de="" =""></ue>	Controls the edge or face of the layer at which the baseline is placed: ue = Baseline is placed at the top edge or face. de = Baseline is placed at the bottom edge or face.				

As discussed in Chapter 1 on page 1, Epi generates a command file for the meshing tool, nx_epi_msh.cmd. For each layer, the above analytic profiles are created with the following parameters [2] in the different sections of this command file:

- The AnalyticalProfile section of the Definition section:
 - Species = ArsenicActiveConcentration | BoronActiveConcentration (for n-type or p-type doping, respectively)
 - Function = General | Error | Gauss (for linear, error, or Gaussian function doping profile, respectively)
 - LateralFunction = Erf (Factor=0) (for error and Gaussian profiles)
- The AnalyticalProfile section of the Placements section:
 - The baseline for each layer is the bottom or top edge (2D) or face (3D), depending on the specification of ue | de in the Doping field (see Table 7 on page 16).
 - The variable Direction is not specified in the ReferenceElement section since the function values are computed on both sides of the baseline.
 - All analytic doping profiles are placed using the EvaluateWindow section. For each layer, the domain for the evaluation of the profile is the region name and DecayLength=0.
 - The variable Replace is not specified.

As discussed in Creating user-defined parameter files for regions with doping/mole-fraction profiles on page 29, a default value for the reference doping concentration must be defined for layers with graded doping profiles. The command default is used for this purpose.

Mole-fraction profiles

The mole-fraction information about layers consisting of ternary or quaternary compound semiconductor materials is described in the MoleFraction field, which is empty for elemental or binary semiconductors. A constant mole fraction or a linearly graded mole-fraction profile can be specified using the commands in Table 8 on page 18. These commands create region-based mole-fraction profiles for the layer in the y-direction.

A default reference x-mole fraction value must be defined for layers with graded x-mole fraction profiles (see Creating user-defined parameter files for regions with doping/mole-fraction profiles on page 29). The command default is used for this purpose.

Epi command file

Currently, this feature does not support layers with graded y-mole NOTE fraction profiles.

Table 8 Commands for MoleFraction field

Command	Description			
Constant mole fraction				
<xmole></xmole>	Constant x-mole fraction for ternary compound semiconductors.			
(<xmole> <ymole>)</ymole></xmole>	Constant x-mole fraction and y-mole fraction for quaternary compound semiconductors.			
Linear mole-fraction profile in y-direction				
<pre>(lin <xmoletop> <xmolebot>) (default <xmole>)</xmole></xmolebot></xmoletop></pre>	Linear region-based x-mole fraction profile with a default reference x-mole fraction value of <xmole>.</xmole>			
(y lin <ymoletop> <ymolebot>)</ymolebot></ymoletop>	Linear region-based y-mole fraction profile [2].			
xMoleTop yMoleTop	The value of x-mole fraction or y-mole fraction at the top edge of the layer.			
xMoleBot yMoleBot	The value of x-mole fraction or y-mole fraction at the bottom edge of the layer.			

Mesh refinement strategy

The global refinement for the complete multilayer stack is defined in the Global section (see Global section on page 9). As discussed in Chapter 3 on page 35, commands for refinements in the x-direction and z-direction are specified in the Sentaurus Structure Editor command file sde dvs.cmd.

The Refinement field in the CSV file performs refinement in the y-direction. Mesh refinement in the y-direction for a particular layer is performed by the commands yref and mbox (see Table 9). The terminology related to mesh refinement is discussed in [2] and [3].

Table 9 Commands for Refinement field

Command	Description		
Uniform regionwise refinement	ent		
(xref <elsize>)</elsize>	Uniform regionwise refinement in the x-direction.		
(yref <elsize>)</elsize>	Uniform regionwise refinement in the y-direction.		
elsize	Specifies the element size (mesh spacing) in the appropriate direction. By default, the element size for the x-direction and z-direction is the width and depth of the structure, respectively.		
(yref qw)	Creates a three-point quantum-well mesh in the y-direction [4].		

Table 9 Commands for Refinement field

Command	Description		
Multibox regionwise refinement			
(mbox <minelsize> <ratio> <direction>)</direction></ratio></minelsize>	Defines a multibox regionwise meshing strategy for a layer in the y-direction by specifying:		
	minelsize: Specifies the minimum element size in the y-direction. By default, the minimum element size in the x-direction and z-direction is the width and depth of the structure, respectively. The maximum element size in the x-, y-, and z-direction is the width, thickness, and depth of the structure, respectively.		
	ratio: The ratio controls how fast the mesh spacing increases from the minimum to the maximum value. Unlike the convention that Sentaurus Structure Editor uses, ratio is a positive number between 1 and 2.		
	 direction: Controls the edge (2D) or the face (3D) of the multibox from which the meshing-line density grading starts. Options are: direction=up: Grading starts from the top edge of the layer, that is, the mesh spacing increases from minimum to maximum in the positive y-direction. direction=down: Grading starts from the bottom edge of the layer, that is, the mesh spacing increases from minimum to maximum in the negative y-direction. direction=both: Grading starts from both edges. The mesh spacing is minimum at the top and bottom of the layer, and increases in both directions towards the center of the layer. This option is useful for creating a fine mesh at interfaces. 		

Material and Interface section

MatPar generates the main material parameter file required by Sentaurus Device as well as the user-defined material parameter files. User-defined parameter files are defined in Overview on page 37.

MatPar can generate following types of user-defined material parameter file:

- Materialwise (see Materialwise user-defined parameter file on page 20)
- Regionwise (see Regionwise user-defined parameter file on page 22)
- Materialwise interface (see Creating materialwise interface parameter files on page 30)

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The main parameter file contains a list of references to the user-defined material parameter files by using the keyword Insert [4]. For example, by default, the main parameter file n@node@_mpr.par generated by MatPar for the structure listed in Table 6 on page 14 contains the following statements:

```
Material = "GaAs" { Insert = "./npar/n5_GaAs.par" }
Material = "MgF" { Insert = "./npar/n5_MgF.par" }
Region = "fsf" { Insert = "./npar/n5_AlGaAs_0.8.par" }
Region = "emitter" { Insert = "./npar/n5_GaAs.par" }
MaterialInterface = "GaAs/AlGaAs" { Insert = "./npar/n5 GaAs AlGaAs.par" }
```

MatPar creates the user-defined parameter files by processing source parameter files, either <material>.tclor<material>.par (see Source parameter files on page 52). In the above example:

- The first two statements correspond to materialwise parameter files.
- The next two statements correspond to regionwise parameter files.
- The last statement corresponds to a materialwise interface parameter file.

The main parameter file is created in the epi subdirectory, and all the user-defined parameter files are created in the epi/npar subdirectory.

NOTE You cannot change these locations.

Materialwise user-defined parameter file

If many regions share the same material, a single user-defined parameter file can be created for the material. Such a file is a *materialwise parameter file*.

To create a materialwise parameter file:

1. Leave the SourceParFile field empty for regions in the Layers section:

```
# Layers section
<Region>, <Material>,, <Thickness>, <Doping>, <MoleFraction>, <Refinement>,
<Extension>
```

2. Append a statement for each such material in the Material and Interface section. If the source parameter file is a <material>.par file, the Region, Thickness, Doping, MoleFraction, Refinement, and Extension fields are empty in each statement:

```
# Material and Interface section
, <Material>, <material.par>,,,,,
```

- 3. If a Tcl source parameter file is used to create the materialwise parameter file:
 - For binaries, a reference doping-concentration value is required by the model files and is specified as follows (see Creating user-defined parameter files for regions with doping/mole-fraction profiles on page 29):

```
# Material and Interface section
, <Material>, <material.tcl>,, <Doping>,,,
```

• For ternaries and quaternaries, a reference doping-concentration and mole-fraction value is required (see Creating user-defined parameter files for regions with doping/mole-fraction profiles on page 29):

```
# Material and Interface section
# Ternary
, <Material>, <material.tcl>,, <Doping>, <xMole>,,
# Quaternary
, <Material>, <material.tcl>,, <Doping>, (<xMole yMole>),,
```

Another method for specifying the reference doping-concentration value is to:

1. Add the following in the CSV file:

```
# Material and Interface section
, <Material>, <material.tcl>,,,,
```

2. Specify the following in the <material>.tcl file:

```
if {[info exists doping] && ([string trim $doping] =="")} {
   set doping <user_defined_value>
}
```

This method can also be used to specify xMole and yMole in the <material>.tcl files for ternaries and quaternaries.

In general, one materialwise user-defined parameter file can be created for each material.

For the structure in Table 6 on page 14, both cap and base regions are GaAs layers. A single materialwise parameter file, n5_GaAs.par, for these regions can be created by specifying the following in the CSV file:

```
# Global section
parFileMask=./npar/n(node)_(material)_(xMole).par
# Layers section
cap,GaAs,,0.5,-5.00e19,,(yref 0.1),
base,GaAs,,2.5,1.00e17,,(mbox 0.05 1.1 both),Recombination(Radiative)
# Material and Interface section
,GaAs,GaAs.tcl,,1.00e18,,,
```

Here, a reference doping-concentration value of 1e18 is used for both GaAs regions, the cap and base.

The name of the regionwise parameter files is controlled by the variable parFileMask (see Naming parameter files). In the above example, since the doping variable is not included in parFileName (defined in Naming parameter files) and there is no x-mole fraction value for GaAs, the materialwise parameter file name for GaAs is n5 GaAs.par.

Regionwise user-defined parameter file

In general, each layer in the Layers section of the CSV file is defined as a region. If a regionwise parameter file is required, the source parameter file is specified in the SourceParFile field of the corresponding layer definition in the Layers section. In general, one regionwise user-defined parameter file can be created for each layer in the multilayer stack.

For example, for the structure in Table 6 on page 14, AlgaAs.tcl and GaAs.tcl are specified for the fsf and emitter regions, respectively. Therefore, the regionwise parameter files n5_AlgaAs_0.8.par and n5_GaAs.par are created for the fsf and emitter regions, respectively:

```
# Global section
parFileMask=./npar/n(node)_(material)_(xMole).par
# Layers section
fsf,AlGaAs,AlGaAs.tcl,0.03,-4.00e18,0.8,(yref 0.01),
emitter,GaAs,GaAs.tcl,0.5,-5.00e17,,(mbox 0.05 1.1 both),
Recombination(Radiative)
```

The name of the regionwise parameter files is controlled by the variable parFileMask (see Naming parameter files). In the above example, since xMole is specified in parFileName and there is no x-mole fraction value for GaAs, the regionwise parameter file names for the fsf and emitter regions are n5 AlGaAs 0.8.par and n5 GaAs.par, respectively.

Naming parameter files

The name of the regionwise and materialwise user-defined parameter files and the directory for these parameter files are defined by the variable parFileMask in the Global section of the CSV file using the syntax:

```
parFileMask=./npar/<parFileName>.par
```

All paths in the command files of Epi and MatPar are specified relative to the epi subdirectory, where ./npar specifies that the user-defined parameter files are stored in the epi/npar subdirectory.

NOTE The location for storing the user-defined parameter files cannot be changed.

The variable parFileName specifies the name of the user-defined parameter file. This name consists of a string formed by combining the values of the physical variables, corresponding to some fields in the CSV file, separated by underscores. These variables are described in Table 10. The complete string for parFileName is:

```
parFileName=n(node)_(material)_(doping)_(xMole)_(yMole)
```

Using the variables doping, xMole, and yMole is optional.

NOTE For binaries, xMole=" ". For binaries and ternaries, yMole=" ". Empty strings are omitted from file names. The underscore preceding the empty string is also omitted.

Table 10 Variables used in parFileName

Variable	Description	
parFileDir	Directory for saving user-defined parameter files, which is ./npar.	
n (node)	Node number of MatPar in the Sentaurus Workbench project.	
material	Layer material.	
doping	Doping concentration of each layer: positive for n-type and negative for p-type semiconductor. This variable is optional.	
xMole	The x-mole fraction of the layer. For binaries, xMole=" ". This variable is optional.	
yMole	The y-mole fraction of the layer. For binaries and ternaries, yMole=" ". This variable is optional.	

Naming materialwise user-defined parameter files

The default value of parFileName for materialwise user-defined parameter files is:

```
parFileName=n(node) (material)
```

If you do not specify parFileMask, the file name of the materialwise user-defined parameter file has the format n(node) (material).par.

If doping is included in parFileName and a doping concentration value is specified in the Material and Interface section, the materialwise parameter file name has the format $n(node)_{(material)_{(doping)}}$. par. If the doping concentration value is not specified in the Material and Interface section, the materialwise parameter file name has the format $n(node)_{(material)}$. par.

Epi command file

If xMole and yMole are included in parFileName, and the mole-fraction value is also specified in the Material and Interface section, the materialwise parameter file name has the format:

- n(node) (material) (doping) (xMole).par for ternaries.
- n(node) (material) (doping) (xMole) (yMole).par for quaternaries.

If the mole-fraction values are not specified in the Material and Interface section, the materialwise parameter file name has the format n(node) (material).par.

Naming regionwise user-defined parameter files

The default value of parFileName for regionwise user-defined parameter files is:

```
parFileName=n(node) (material) (xMole)
```

If you do not specify parFileMask, the file name of the regionwise user-defined parameter file has the format:

- n(node) (material) (xMole).par for ternaries.
- n(node)_(material).par for binaries.

If regions have constant doping and mole fractions, the corresponding layer values are used for doping, xMole, and yMole in parFileName. If regions have doping and x-mole fraction profiles, the default value is used (see Creating user-defined parameter files for regions with doping/mole-fraction profiles on page 29).

NOTE The case of y-mole fraction profiles is not yet supported.

Order in which MatPar processes source parameter files

MatPar processes the source parameter files to create user-defined parameter files in the following order:

- 1. If the variable substrate is defined in MatPar_mpr.cmd, the Tcl source parameter file corresponding to the substrate material is processed first.
- 2. The source parameter files specified in the materialwise parameter file definition in the Material and Interface section of the CSV file are processed sequentially in the order in which they appear in this section.
- 3. The source parameter files specified in the Layers section of the CSV file are processed sequentially in the order in which they appear in this section.
- 4. The source parameter files specified in the materialwise interface parameter file definition in the Material and Interface section of the CSV file are processed sequentially in the order in which they appear in this section.

Example 1

For the structure in Table 6 on page 14, the complete string for parFileName is used; therefore, parFileMask is:

```
parFileMask=./npar/n(node) (material) (doping) (xMole) (yMole).par
```

In this case, the main parameter file generated by MatPar for the structure listed in Table 6 contains the following statements:

```
Material = "GaAs" { Insert = "./npar/n5_GaAs.par" }
Material = "MgF" { Insert = "./npar/n5_MgF.par" }
Region = "fsf" { Insert = "./npar/n5_AlGaAs_-4.00e18_0.8.par" }
Region = "emitter" { Insert = "./npar/n5_GaAs_-5.00e17.par" }
MaterialInterface = "GaAs/AlGaAs" { Insert = "./npar/n5 GaAs AlGaAs.par" }
```

MatPar processes the source parameter files in the following order:

- 1. GaAs.tcl to create the materialwise parameter file n5_GaAs.par, which Sentaurus Device uses for all GaAs regions that do not use regionwise parameter files. Here, n5 GaAs.par is used for the cap and base regions.
- 2. MgF.par to create the materialwise parameter file n5_MgF.par, which is used for all MgF₂ regions.
- 3. AlGaAs.tcl to create the regionwise parameter file n5_AlGaAs_-4.00e18_0.8.par, which is used for the fsf region.
- 4. GaAs.tcl to create the regionwise parameter file n5_GaAs_-5.00e17.par, which is used for the emitter region.
- 5. Ge.tcl to create the regionwise parameter file n5_Ge_1.00e18.par, which is used for the substrate region.
- 6. GaAs_AlGaAs.par to create the materialwise interface parameter file n5_GaAs_AlGaAs.par, which is used for all GaAs/AlGaAs interfaces.

In this example, since empty strings are omitted from file names, the regionwise parameter file for fsf is n5 AlGaAs -4.00e18 0.8.par.

NOTE You must take into account the order in which MatPar processes the source parameter files when specifying the source parameter file names and parFileMask.

If the default value of parFileMask is used, the name of a materialwise parameter file is the same as the name of a regionwise parameter file for elemental and compound semiconductors. In this case, a parameter file created from a source parameter file specified in the Material and Interface section may be overwritten by a parameter file created from a source parameter file specified in the Layers section. As a result, instead of using a materialwise parameter file for a

particular material, you may use unintentionally a regionwise parameter file. This is illustrated in Example 2.

Example 2

For the structure in Table 6 on page 14, if a regionwise parameter file is required for the emitter region and a materialwise parameter file is required for all other GaAs regions, the command file is:

```
# Layers section
cap,GaAs,,0.5,-5.00e19,,(yref 0.1),
fsf,AlGaAs,AlGaAs.tcl,0.03,-4.00e18,0.8,(yref 0.01),
emitter,GaAs,GaAs.tcl,0.5,-5.00e17,,(mbox 0.05 1.1
both),Recombination(Radiative)
base,GaAs,,2.5,1.00e17,,(mbox 0.05 1.1 both),Recombination(Radiative)
# Material and Interface section
,GaAs,GaAs.par,,1.00e18,,,
,MgF,MgF.par,,,,,
```

Here, GaAs.tcl has been replaced with GaAs.par in the materialwise parameter file definition for GaAs. In addition, the substrate region and materialwise interface parameter file definition have been removed.

Since parFileMask is not specified, MatPar uses the default value of parFileMask. As a result, MatPar processes the source parameter files in the following order:

- 1. Source parameter files in the Material and Interface section:
 - a) GaAs.par is processed to create the materialwise parameter file n5 GaAs.par.
 - b) MgF.par is processed to create n5 MgF.par.
- 2. Source parameter files in the Layers section:
 - a) AlGaAs.tcl is processed to create n5 AlGaAs -4.00e18 0.8.par.
 - b) GaAs.tcl is processed to create the regionwise parameter file n5_GaAs.par, which is used for the emitter region.

The materialwise parameter file n5_GaAs.par created in Step 1a is overwritten by the regionwise parameter file created in Step 2b. The regionwise parameter file n5_GaAs.par is used for all GaAs regions instead of a separate regionwise parameter file for the emitter region and a materialwise parameter file for all other GaAs regions.

In such cases, you must ensure that the source parameter file for a particular material is the same in the Material and Interface section and the Layers section. If different source parameter files are specified for the same material, this problem can also be solved by using:

```
parFileMask=./npar/n(node)_(material)_(doping).par
```

With the proper choice of parFileName, MatPar can create different regionwise parameter files for two different regions with the same material but different doping concentrations. This is illustrated in Example 3.

Example 3

For the structure in Table 6 on page 14, MatPar can create different regionwise parameter files for the cap and emitter regions as follows:

- Specify parFileMask=./npar/n(node) (material) (doping).par.
- Specify GaAs.tcl in the cap layer definition.

As a result, MatPar creates the main parameter file containing the statements:

```
Material = "GaAs" { Insert = "./npar/n5_GaAs.par" }
Material = "MgF" { Insert = "./npar/n5_MgF.par" }
Region = "cap" { Insert = "./npar/n5_GaAs_-5.00e19.par" }
Region = "fsf" { Insert = "./npar/n5_AlGaAs_-4.00e18.par" }
Region = "emitter" { Insert = "./npar/n5_GaAs_-5.00e17.par" }
MaterialInterface = "GaAs/AlGaAs" { Insert = "./npar/n5 GaAs AlGaAs.par" }
```

Here, both the cap and emitter regions are made of GaAs, but they have different doping concentrations. Since the variable doping is included in parFileName, MatPar creates different parameter files for these regions. Instead of using the materialwise parameter file n5_GaAs.par, a regionwise parameter file, n5_GaAs_-5.00e19.par, is used for the cap region. The base region continues to use n5_GaAs.par since GaAs.tcl was not specified in the base layer definition in the CSV file.

Creating user-defined parameter files for regions/materials not in Epi structure

As discussed in Chapter 3 on page 35, Sentaurus Structure Editor further processes the multilayer stack created by Epi. These processing steps may result in the:

- Formation of new regions (regions not included in the CSV file).
- Addition of regions with new materials (materials not included in the CSV file).
- Removal of a region that was defined in the CSV file.

You can create user-defined parameter files for the first two cases by specifying appropriate source parameter files in the CSV file.

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Epi command file

To create user-defined parameter files for materials not included in the CSV file, specify the new material name and source parameter file name in the Material and Interface section of the CSV file (see Materialwise user-defined parameter file on page 20):

```
# Material and Interface section
, <New Material>, <SourceParFile>,,,,
```

For example, for the multilayer stack defined in Table 6 on page 14, an MgF₂ layer is deposited using Sentaurus Structure Editor. Therefore, the following is included in the CSV file:

```
# Material and Interface section
, MgF, MgF.par,,,,
```

To create regionwise or materialwise parameter files for new regions, follow the procedure in Materialwise user-defined parameter file on page 20 with the modification of leaving the Thickness and Refinement fields empty in the Layers section:

```
# Layers section
<New_Region>, <Material>, <SourceParFile>,, <Doping>, <MoleFraction>,,
<Extension>
```

Epi does not create the <New_Region> layer since the Thickness field is empty. Epi uses the Doping and MoleFraction fields to define the name of the regionwise parameter file for <New_Region>, and MatPar uses these fields to create the regionwise parameter file.

If a region included in the CSV file is removed by Sentaurus Structure Editor, leave the SourceParFile, Refinement, and Extension fields empty for that region. MatPar does not create a parameter file for that region:

```
# Layers section
<Region>, <Material>,, <Thickness>, <Doping>, <MoleFraction>,,
```

This information is applicable when Sentaurus Structure Editor creates lumped regions. If Sentaurus Structure Editor separates a region called emitter into two disconnected lumps and if the new region names are emitter_lump_1 and emitter_lump_2, the following listing in the CSV file creates parameter files for the lumped regions, and a parameter file is not created for the emitter region:

```
# Layers section
emitter, GaAs,, 2, -5.00e17,,,
emitter_lump_1, GaAs, GaAs.tcl,, -5.00e17,,,
emitter_lump_1, GaAs, GaAs.tcl,, -5.00e17,,,
```

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Creating user-defined parameter files for regions with doping/molefraction profiles

For each layer in the multilayer stack, the physical variables doping, xMole, and yMole are used to:

- Define the name of the regionwise user-defined parameter file (see Materialwise user-defined parameter file on page 20).
- Compute material properties by some of the model files (see Model files on page 58). In the case of the TableODB parameter section, for some models in the Material Parameter Database¹, these variables are also used to select the appropriate data file required for printing this section.

For each layer, these variables should have a unique value. By default, these variables have a unique value for regions with uniform doping concentration or mole fraction. A unique value for doping and xMole can be assigned to regions with doping and x-mole fraction profiles by using the command default in the Doping and MoleFraction fields in the Layers section of the CSV file as follows:

```
(cprofile definition>) (default <value>)
```

The syntax for specifying <profile_definition> is discussed in Table 7 on page 16 and Table 8 on page 18.

For example:

```
# Global section
parFileMask=./npar/n(node)_(doping)_(xMole).par
# Layers section
region1, GaAs, GaAs.tcl, 5,, (lin 1e15 1e18)(default 1e17),, (yref 1)
region2, AlGaAs, AlGaAs.tcl, 2, 1e18, (lin 0 1)(default 0.5),, (yref 1)
```

NOTE The use of this syntax for regions with y-mole fraction profiles is not yet supported. In addition, the use of the default command is not required if the source parameter file is a <material>.par file.

For binaries, if the structure consists of several regions with identical materials and doping profiles, a unique value for doping can be specified in the Material and Interface section without using the default command as follows:

- 1. Omit the source parameter file name and the default command from the Doping field of the regions.
- 2. Include the corresponding default value in a Material and Interface section.

^{1.} For example, the model file pardb/GaAs/Optics/TableODB/Levinshtein.tcl implements the doping-dependent complex refractive index model from Levinshtein [5].

For example:

```
# Global section
$global parFileMask=/npar/n(node)_(material)_(doping).par
# Layers section
region1, GaAs,, 5,, (lin 1e15 1e18),, (yref 1)
region2, GaAs,, 2,, (lin 1e15 1e18),, (yref 1)
region3, GaAs, GaAs.tcl, 0.3,, (lin 5e18 6e18)(default 1e15),, (yref 0.1)
# Material and Interface section
, GaAs, GaAs.tcl,,, 1e17,,
```

Here, a materialwise parameter file nX_GaAs_1e17.par is created for region1 and region2, and a regionwise parameter file nX GaAs 6e18.par is created for region3.

Creating materialwise interface parameter files

A user-defined materialwise interface parameter file can be created by using the following syntax in the Material and Interface section:

```
,<material1/material2>,,<SourceParFile>,,,
```

MatPar uses the source parameter file SourceParFile to create a materialwise interface parameter file, n(node)_<material1>_<material2>.par, for the interface between material1 and material2.

NOTE Here, the source parameter file should have the extension .par. A Tcl source parameter file cannot be specified.

In general, one materialwise interface parameter file can be created for each pair of material interfaces.

Example 4

For the structure in Table 6 on page 14, MatPar can create a materialwise interface parameter file for GaAs/AlGaAs interfaces using the commands:

```
# Material and Interface section
# Materialwise interface parameter file definition
,GaAs/AlGaAs,GaAs AlGaAs.par,,,,
```

In this case, MatPar uses the parameter file GaAs_AlGaAs.par to create the user-defined materialwise interface parameter file nx_GaAs_AlGaAs.par. As a result, the main parameter file contains the line:

```
MaterialInterface = "GaAs/AlGaAs" { Insert = "./npar/n5 GaAs AlGaAs.par" }
```

and Sentaurus Device uses this parameter file for all GaAs/AlGaAs interfaces in the structure.

Extension columns

The Extension field can have arbitrary content and can be used by MatPar to insert this content in the preprocessed Sentaurus Device command file. There can be multiple columns in the Extension field.

NOTE By default, there is no Extension field. In addition, the Extension field is not applicable to the Material and Interface section.

Creating multiple columns

To create multiple columns in the Extension field, use the command:

```
$qlobal append columnNames <extensionColumnName1> <extensionColumnName2> ...
```

where extensionColumnName1 and extensionColumnName2 are the column names of the Extension field. These columns are saved in a Tcl array in the file n@node@_epi.tcl. The content of these columns can be accessed from the MatPar command file (see Inserting Extension columns in Sentaurus Device command file on page 49).

Extended commands

Epi uses the extended commands repeat, end, and i to generate a substack of layers repeatedly. This reduces the manual entry of the required number of layers for highly repetitive structures such as distributed Bragg reflectors (DBRs) in vertical-cavity surface-emitting lasers.

Table 11 shows part of a multiple—quantum well structure, in which the quantum well (qwell\$i) and the barrier (qwbarrierSCH\$i) are repeated.

Table 11 Epi command file consisting of part of the multiple-quantum well structure

Region	Material	SourcePar File	Thickness	Doping	Mole Fraction	Refinement	Extension
pbarrierSCH	GaN	GaN.tcl	0.007	-3.00e15		(mbox 0.001 1.2 both)	
\$repeat 2						(yref qw)	
qwell\$i	InGaN	InGaN.tcl	0.001	-3.00e15	0.08	(yref qw)	Physics(region= qwell\$i) {Recombination (-Radiative) Active}

Epi command file

Table 11 Epi command file consisting of part of the multiple-quantum well structure

Region	Material	SourcePar File	Thickness	Doping	Mole Fraction	Refinement	Extension
qwbarrierSCH\$i	GaN	GaN.tcl	0.007	-3.00e15		(mbox 0.001 1.2 both)	
\$end							
nbarrier	GaN	GaN.tcl	0.007	-3.00e15		(mbox 0.001 1.2 both)	

The syntax for the repeat command is:

\$repeat <N> layer1 layer2 \$end

All lines between \$repeat and \$end are repeated <N> times. In each line, the string \$i is replaced by the line number starting from 1 to <N>.

For example, after processing the CSV file consisting of the structure in Table 11 on page 31, Epi generates the structure in Table 12.

NOTE The region names in the region columns as well as the extension columns are numbered.

Table 12 Structure generated from Epi command file containing structure in Table 11

Region	Material	SourcePar File	Thickness	Doping	Mole Fraction	Refinement	Extension
pbarrierSCH	GaN	GaN.tcl	0.007	-3.00e15		(mbox 0.001 1.2 both)	
qwell1	InGaN	InGaN.tcl	0.001	-3.00e15	0.08	(yref qw)	Physics(region= qwell1) {Recombination (-Radiative) Active}
qwbarrierSCH1	GaN	GaN.tcl	0.007	-3.00e15		(mbox 0.001 1.2 both)	
qwell2	InGaN	InGaN.tcl	0.001	-3.00e15	0.08	(yref qw)	Physics (region= qwell2) {Recombination (-Radiative) Active}

Table 12 Structure generated from Epi command file containing structure in Table 11

Region	Material	SourcePar File	Thickness	Doping	Mole Fraction	Refinement	Extension
qwbarrierSCH2	GaN	GaN.tcl	0.007	-3.00e15		(mbox 0.001 1.2 both)	
nbarrier	GaN	GaN.tcl	0.007	-3.00e15		(mbox 0.001 1.2 both)	

References

- [1] Sentaurus Workbench User Guide, Version A-2007.12, Mountain View, California: Synopsys, Inc., 2007.
- [2] *Mesh Generation Tools User Guide*, Version A-2007.12, Mountain View, California: Synopsys, Inc., 2007.
- [3] Sentaurus Structure Editor User Guide, Version A-2007.12, Mountain View, California: Synopsys, Inc., 2007.
- [4] Sentaurus Device User Guide, Version A-2007.12, Mountain View, California: Synopsys, Inc., 2007.
- [5] M. Levinshtein, S. Rumyantsev, and M. Shur, *Handbook Series on Semiconductor Parameters, Si, Ge, C (Diamond), GaAs, GaP, GaSb, InAs, InP, InSb*, vol. 1, Singapore: World Scientific, 1996.

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CHAPTER 3 Using Sentaurus Structure Editor

This chapter discusses how Epi works with Sentaurus Structure

Overview

Epi creates the multilayer stack or wafer, whereas Sentaurus Structure Editor is used to modify the structure and to create the complete device that can be used for performing device simulation.

Figure 3 shows a multilayered GaAs solar cell structure, illustrating the differences in the structure created by Epi and Sentaurus Structure Editor.

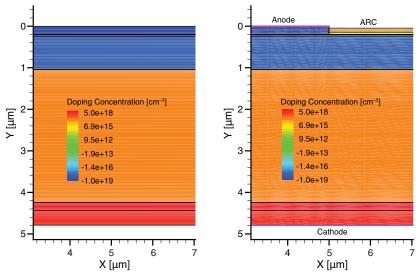


Figure 3 (*Left*) Multilayer stack from Epi and (*right*) device structure from Sentaurus Structure Editor

Scheme script files

In general, Sentaurus Structure Editor performs the following steps:

- The Scheme script file n@node@ epi.scm, created by Epi, contains commands for:
 - Creating the multilayer stack.
 - Creating each layer as rectangular regions.
 - Adding doping and mole-fraction profiles to the structure.
 - Performing regionwise mesh refinement in the y-direction for each layer.

The file is sourced in the Sentaurus Structure Editor command file sde_dvs.cmd using the Scheme command:

```
(load "n@node|epi@ epi.scm")
```

After this command, all Epi variables are available to the Sentaurus Structure Editor command file as Scheme variables.

Various device-processing steps such as etching and additional layer deposition can be performed using the Scheme variables Y0 <reqion> and Y1 <reqion>.

Y0_<region> is the y-coordinate of the top edge of the region, and Y1_<region> is the y-coordinate of the bottom edge of the region.

The file n@node@_epi.scm defines these variables for each region. For the solar cell structure in Figure 3 on page 35, the top GaAs layer is etched partially, and a double-layer antireflective coating is deposited.

- Electrical contacts are added to the multilayer stack.
- Mesh refinement commands for refinements in the x-direction and z-direction are added. For example, for the solar cell structure in Figure 3, a fine mesh is added under the contacts in the x-direction. In addition, a finer mesh is added in the y-direction in the top layer to resolve the optical generation profile.
- The complete device structure is generated using Sentaurus Mesh and is stored in the file n@node@_msh.tdr.

Epi creates the predefined Epi variables Ytop and Ybot (see Table 4 on page 11) and defines the corresponding Scheme variables Ytop and Ybot in n@node@_epi.scm. These Scheme variables can be used to define the top and bottom electrodes in a device. For example, a contact at the top and bottom of a device can be added with the following Scheme commands:

```
(sdegeo:define-2d-contact (find-edge-id (position (/ wtop 2) Ytop 0)) "anode")
(sdegeo:define-2d-contact (find-edge-id (position (/ wbottom 2) Ybot 0))
    "cathode")
```

where wtop is the width of the top layer, and wbottom is the width of the bottom layer.

CHAPTER 4 Using MatPar

This chapter describes how to use MatPar with Sentaurus Device.

Overview

Sentaurus Device requires a main parameter file that contains a list of references to other material parameter files.

A material parameter file is divided into several parameter sections. Each parameter section corresponds to a single material property or a group of related material properties. The dependency of a material property on physical variables such as temperature, doping concentration, mole fraction, and the wavelength of incident light is described by a physical model.

These models are represented usually by equations. The coefficients in these equations are called *model parameters*. The collection of model parameters for a particular model is called a *model parameter set*. A parameter section in the parameter file defines the values of model parameters for a specific model.

The model parameter set consisting of a specific value for each model parameter in the set is called a *model parameter set value*. For example, the Bandgap section in the parameter file corresponds to the band gap and electron affinity of a material. It contains model parameter set values for the Varshni bandgap model [1], which is the model implemented in Sentaurus Device. The Varshni model is described by:

$$E_{g}(T) = E_{g}(0) + \frac{\alpha T_{\text{par}}^{2}}{T_{\text{par}} + \beta} - \frac{\alpha T^{2}}{T + \beta}$$

$$\tag{1}$$

The Varshni bandgap model describes the variation of band gap with temperature. Here, band gap is a material property, and T is a physical variable. α , β , $E_{\rm g}(0)$, and $T_{\rm par}$ are the model parameters of the Varshni model and are represented by alpha, beta, Eg0, and Tpar in the Bandgap section, respectively. A typical Bandgap section in the parameter file is:

```
Bandgap
{ * Eg = Eg0 + alpha Tpar^2 / (beta + Tpar) - alpha T^2 / (beta + T)
 * Parameter 'Tpar' specifies the value of lattice
 * temperature, at which parameters below are defined
 * Chi0 is electron affinity.
   Chi0 = 4.07  # [eV]
   Bgn2Chi = 0.5  # [1]
```

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```
Eg0 = 1.519 # [eV]
alpha = 5.4050e-04 # [eV K^-1]
beta = 2.0400e+02 # [K]
Tpar = 0.0000e+00 # [K]
}
```

The set of model parameters {Chi0, Bgn2Chi, Eg0, alpha, beta, Tpar} is the complete model parameter set of the Varshni model. The set of values of these model parameters {4.07, 0.5, 1.519, 5.4050e-04, 2.0400e+02, 0.0000e+00} is the model parameter set value.

In this manual, the models implemented in Sentaurus Device are called *default models*, and the models not implemented in Sentaurus Device are called *new models*.

The equations for the default models are implemented in Sentaurus Device [2]. Sentaurus Device provides built-in default parameter values in the default material parameter files for many materials.

Sentaurus Device uses the default model parameter set to calculate the value of material properties using the default models for each parameter section. For example, the above Bandgap section defines the default parameter values for the default GaAs parameter file. To use a different set of model parameter values for device simulation, a new material parameter file can be created by redefining the default model parameter values. For example, a user-defined parameter file for GaAs can be created with a different set of model parameter values for the Bandgap section:

The new material parameter file is called the user-defined material parameter file. This approach of creating user-defined material parameter files is referred to as the *Sentaurus Device approach*.

MatPar provides an additional approach – the MatPar approach – for creating user-defined parameter files. MatPar is used to implement the default models with either the default model parameter set value or model parameter set value obtained from the literature.

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User-defined models can also be added to the Material Parameter Database. MatPar can create user-defined parameter files consisting of model parameter set values computed from new models or default models for all parameter sections.

Starting MatPar

The source file for MatPar is a Tcl script file, mpr.tcl, which is located in the lib subdirectory. The Tcl interpreter gtclsh is used to execute MatPar.

MatPar can be started either from the command line or Sentaurus Workbench. MatPar is driven by a command file with the default name MatPar_mpr.cmd.

To start MatPar from the command line, execute the following command from inside the epi subdirectory:

```
gtclsh ../lib/mpr.tcl <command file>
```

The file gtooldb.tcl contains appropriate commands to launch MatPar automatically through the Scheduler when working inside Sentaurus Workbench.

The MatPar command file MatPar_mpr.cmd can be accessed directly from Sentaurus Workbench.

To open MatPar mpr.cmd in SEdit:

Right-click the MatPar icon in the tool row, and select Edit Input > Commands.

MatPar Components

MatPar consists of:

- Material Parameter Framework (see Material Parameter Framework on page 40).
- Material Parameter Database (see Material Parameter Database on page 41).
- Material Parameter Plotter (see Material Parameter Plotter on page 74).

The main steps to create user-defined parameter files using the MatPar approach are:

- 1. Model specification in Tcl source parameter files (see Source parameter files on page 52).
- 2. Model parameter set computation in model files (see Model files on page 58).
- 3. Parameter section printing in user-defined parameter files (see Parameter Initialization section and Parameter Printing section on page 56).

MatPar creates each user-defined regionwise or materialwise parameter file by processing a source parameter file (either <material>.tcl or <material>.par).

The <material>.tcl files are called Tcl source parameter files. There is one Tcl source parameter file for each material. These files contain user-specified model names for each parameter section to be printed in the user-defined parameter file. The model parameter set for a particular model is computed in model files (<model>.tcl) in the Material Parameter Database.

MatPar processes each Tcl source parameter file, computes the model parameter set from model files, and prints the parameter sections in the user-defined parameter files by invoking print procedures. If the source parameter file is a <material>.par file, the user-defined parameter file is a copy of the source parameter file. Detailed steps are discussed in How MatPar creates user-defined parameter files on page 73.

For a particular material and material property, different models as well as different model parameter set values for the same model can be implemented in the Material Parameter Database. The default models are also implemented.

In the MatPar approach for creating user-defined parameter files, the user-defined parameter files are created by MatPar from the user-specified model names in the Tcl source parameter file. You can switch easily between different models for a particular parameter section by changing the model names in the Tcl source parameter file.

Material Parameter Framework

The Material Parameter Framework provides a Tcl-based framework for:

- Creating user-defined material parameter files.
- Implementing material property models.
- Choosing models for a particular material property.
- Computing the model parameter values.
- Printing the user-defined parameter file.

These tasks are achieved by several procedures in the framework. It also includes a collection of Tcl source parameter files in which the model names used for creating the user-defined parameter files are specified. These files are described in Source parameter files on page 52.

All framework files are in the lib and par subdirectories (see Table 2 on page 2).

The file lib/helper.tcl contains helper procedures for the Material Parameter Framework and Epi. It contains several procedures that are useful for computing the material parameters.

Some of these procedures are discussed in Helper procedures for calculating model parameters/material properties on page 69.

The file lib/helper.tcl also includes initProperty, the procedure used to initiate the computation of material parameters. The procedures for printing the parameter sections in the user-defined parameter files are defined in lib/printPar.tcl. Both these procedures are discussed in Parameter Initialization section and Parameter Printing section on page 56.

The file PhysicalConstants.tcl contains definitions of fundamental physical constants, which are useful for computing material properties in some model files (see Input Validation and Header Printing section on page 54).

The file compound_lib.tcl contains procedures for interpolating material parameter/ property values for compound semiconductors. These procedures are discussed in Interpolation procedures for ternary and quaternary compound semiconductors on page 72.

Material Parameter Database

The Material Parameter Database is a collection of model parameters from different references for the material properties of several materials. The model parameters are computed in model files. The directory of the Material Parameter Database is pardb.

Directory structure

The model files are located in a three-level directory structure inside pardb:

<material>//cmaterial>//cmaterial>/<model>.tcl

This directory structure is shown in Figure 4 on page 43 and consists of:

- The <material > directory, which is named after the material.
- The
 ¬ The

The parameterSection subdirectories are named after the corresponding parameter section in the parameter file. For example, the parameter sections Bandgap, TableBGN, eDOSMass, and hDOSMass are grouped under a propertyGroup called BandStructure. Under every <material> directory, there is a directory called BandStructure, which contains the subdirectories Bandgap, TableBGN, eDOSMass, and hDOSMass.

NOTE Currently, only the parameter sections listed in Table 13 can be printed in the user-defined parameter file.

■ The model files: For a particular material and property group, the <parameterSection> subdirectory can contain several model files that correspond to different models or different values of the parameter set for the same model. The names of these model files have the format <model>.tcl, where model is the model name (see Model files on page 58).

Table 13 Grouping of parameter sections in property group

Property group	Parameter section	Print procedure in printPar.tcl
BandStructure	Bandgap	BandgapSection
	delAlamo	delAlamoSection
	eDOSMass	eDOSMassSection
	hDOSMass	hDOSMassSection
	JainRoulston	JainRoulstonSection
	TableBGN	TableBGNSection
Mobility	ConstantMobility	ConstantMobilitySection
	DopingDependence	DopingDependenceSection
	HighFieldDependence	HighFieldDependenceTEM2Section
Optics	FreeCarrierAbsorption	FreeCarrierAbsorptionSection
	RefractiveIndex	RefractiveIndexSection
	TableODB	TableODBSection
Permittivity	Epsilon	EpsilonSection
Quantization	SchroedingerParameters	SchroedingerParametersSection
Recombination	Auger	AugerSection
	BarrierTunneling	BarrierTunnelingSection
	RadiativeRecombination	RadiativeRecombinationSection
	Scharfetter	ScharfetterSection
ThermoTransport	Kappa	KappaSection
	LatticeHeatCapacity	LatticeHeatCapacitySection
Traps	PooleFrenkel	PooleFrenkelSection

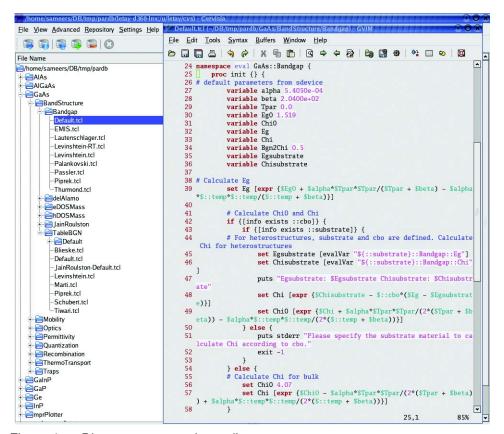


Figure 4 Directory structure in pardb

Adding new models and new materials

New materials and models can be added in the Material Parameter Database for the parameter sections listed in Table 13 on page 42.

To add new models to existing materials in the Material Parameter Database:

- 1. Implement the model in a model file.
- 2. Add the model file to an appropriate corresponding material directory.

To add new models for new materials to the Material Parameter Database:

- 1. Create the corresponding Tcl source parameter file.
- 2. Add the <material > subdirectory under pardb.

If Sentaurus Device does not recognize the material, follow the procedure for adding user-defined materials described in [2].

At least, add the <parameterSection> subdirectories corresponding to the critical models [2].

4. Add the model files to the fersection> subdirectories.

To create a model file, see Sections of model file on page 60.

Model documentation

The Material Parameter Database is documented in HTML format. The documentation summarizes the current lists of materials, property groups, parameter sections, and models in the database as well as describes the models. The header section in the model files provides the model description (see Figure 5 on page 45).

Adding new documentation

If new materials or models are added to the Material Parameter Database, the corresponding documentation can be added to the existing documentation:

Right-click the MatPar icon in the tool row, and select Edit > Refresh Documentation.

Viewing documentation

To view the documentation on UNIX, set the browser by adding the following line to the \$STDB/gpref_<user>.\$STRELEASE file:

```
genesis*WB binaries.editor,html browser:<bre>
```

To access the documentation from the MatPar node on UNIX:

 Right-click the MatPar icon in the tool row, and select Edit > View Parameter Library (HTML).

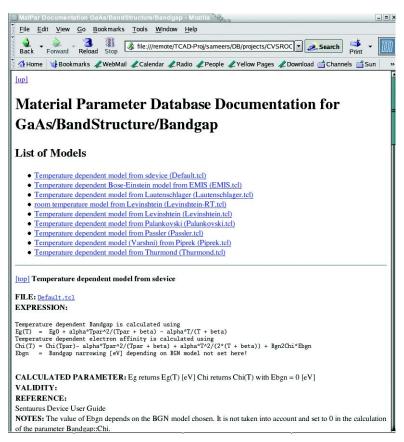


Figure 5 Example of documentation for the GaAs bandgap models

MatPar command file

The command file for MatPar, MatPar_mpr.cmd, is a Tcl script file. It consists of some mandatory and some optional commands. These commands define a few variables and invoke some procedures as described here.

MatPar ignores character strings starting with #. Therefore, the # can be used to insert comments in the command file.

Defining variables in command file

Table 14 summarizes the variables that can be defined in the MatPar command file. MatPar does not define any default values for these variables. All variables are available to the Material Parameter Framework and can be accessed from both Tcl source parameter files and model files.

Table 14 Variables defined in MatPar command file

Variable	Description	Unit	Example
lambda	Wavelength of the incident light on the device.	μm	0.5
parameterOutputFile	The main parameter file required by Sentaurus Device. Must be defined.		n@node@_mpr.par
pardb	Location of the Material Parameter Database.	_	"/pardb"
substrate	Reference material for calculating electron affinity values for heterostructures.	_	GaAs
temp	Operating temperature of the device. Must be defined.	K	300

Variables such as the device-operating temperature, wavelength of incident light on the device, and reference material for electron affinity can be defined in the MatPar command file using the Tcl command set:

```
set temp <value>
set lambda <value>
set substrate <material name>
```

NOTE Since many models are temperature dependent, it is mandatory to define temp. The Sentaurus Workbench project aborts if temp is not defined.

Sentaurus Workbench variables can also be accessed in MatPar_mpr.cmd. This feature can be used to pass the Sentaurus Workbench variables to the Tcl source parameter files and model files.

For heterostructure simulations, the reference material for the electron affinity and conductionband offset (cbo) value of each material with respect to the reference material may be specified (see Simulating band structure of heterostructures on page 63).

In MatPar, this reference material is specified using the Tcl variable substrate in the MatPar command file, and the cbo value for each material is specified in the corresponding Tcl source parameter file using the Tcl variable cbo.

The syntax for specifying the reference material is:

```
set substrate <material>
```

Usually, the substrate material is chosen as the reference material. For the structure defined in Table 6 on page 14, Ge can be defined as the reference material:

```
set substrate Ge
```

In this case, the electron affinity of AlGaAs and GaAs are calculated using the cbo values of AlGaAs and GaAs with respect to Ge, respectively. The cbo values of the materials AlGaAs and GaAs are specified in the respective Tcl source parameter files AlGaAs.tcl and GaAs.tcl.

If substrate is defined, the corresponding <material>.tcl file is always processed first, so that the electron affinity and band gap of the substrate material are computed by MatPar and are available for the calculation of the electron affinity value of each material in the stack.

In the above example, Ge.tcl is processed before processing the other source parameter files. For the definition of cbo and electron affinity calculation, see Simulating band structure of heterostructures on page 63.

parameterOutputFile defines the name of the main parameter file that contains all of the regionwise or materialwise material parameter files. It is mandatory to define this variable since it is required by Sentaurus Device, and the syntax is:

```
set parameterOutputFile <Main parameter file>
```

The location of the Material Parameter Database is defined using the variable pardb, which is specified using the Tcl command set:

```
set ::pardb <location of pardb directory>
```

Since pardb must be defined in the global namespace¹, it is necessary to provide the '::' prefix. The location of the pardb subdirectory is defined with respect to the epi subdirectory. Usually, pardb and epi are at the same level, therefore, pardb is defined by:

```
set ::pardb "../pardb"
```

In addition to defining the above variables, n@node@_epi.tcl, which contains all of the information about the layered structure, is sourced in the MatPar command file:

```
source "./n@node|epi@_epi.tcl"
```

^{1.} Namespaces provide scope for procedures and global variables. A namespace is a collection of procedures and variables. Namespaces ensure that the procedures and variables of a particular namespace do not interfere with the procedures and variables of other namespaces. By default, all Tcl variables are defined in the global namespace of Tcl. The global namespace also contains all global variables and commands. For a detailed discussion, refer to the literature [3].

With this file, MatPar has information as to which source parameter file to process and the name of the corresponding user-defined parameter files. In addition, all of the variables defined in Epi and MatPar are available to the Material Parameter Framework as Tcl variables and can be accessed from both the Tcl source parameter files and model files.

Referencing Sentaurus Workbench variables

The Sentaurus Workbench variables can be referenced in the MatPar command file, Tcl source parameter files, and model files using two methods:

- @-substitution method
- gparam method

The @-substitution method

The usual Sentaurus Workbench syntax can be used in MatPar mpr.cmd as follows:

```
set <Tcl_variable> <@SWB_variable@>
```

This converts the Sentaurus Workbench variable SWB_variable into a Tcl variable Tcl_variable, which can be referenced in all Tcl source parameter files and model files. For example, the Sentaurus Workbench variable temperature can define the Tcl variable temp in MatPar mpr.cmd as follows:

```
set temp @temperature@
```

When temp is defined in the MatPar command file, it is accessible to all Tcl source parameter files and all model files.

The gparam method

The procedure exportParams is defined in the Material Parameter Framework. If the exportParams procedure is invoked in MatPar_mpr.cmd, Sentaurus Workbench variables can be referenced in Tcl source parameter files and model files using the format:

```
$gparam(<SWB variable>)
```

exportParams is invoked from the MatPar command file using the statement:

```
exportParams @node@
```

where @node@, as usual, indicates the node number of MatPar in Sentaurus Workbench.

For example, if a parameter called model is defined in Sentaurus Workbench and its value equals Levinshtein, it can be referenced in any Tcl source parameter file as follows:

```
initProperty $material Permittivity Epsilon $gparam(model)
```

The syntax of the initProperty procedure is discussed in Source parameter files on page 52.

In the Material Parameter Framework, the @-substitution method also works directly in <material>.tcl files. Instead of using the gparam method in the above example, the following command can be used:

```
initProperty $material Permittivity Epsilon @model@
```

Inserting Extension columns in Sentaurus Device command file

When n@node@_epi.tcl is sourced in MatPar_mpr.cmd, the content of all columns in the Extension field can be accessed from MatPar_mpr.cmd using the following Tcl commands in MatPar mpr.cmd:

The foreach Tcl command loops through all region layers for which the extension columns, <extensionColumnName1>, <extensionColumnName2>, and so on are defined. The command:

```
loadLayerVariables $key
```

creates a variable with the same name as the name of the extension column, so that the content of the extension columns can be accessed with the Tcl syntax \$<extensionColumnName> and can be manipulated with user-defined commands:

```
<user-defined commands>
```

For example, to write the content of a single extension column with the name extension in the file n@node@ extension.cmd, use:

```
set FID [open "n@node@_extension.cmd" w]
foreach key [getLayerKeyList "region,*,extension"] {
   loadLayerVariables $key
```

```
puts $FID "$extension"
}
close $FID
```

The content of the n@node@_extension.cmd file can be inserted in the preprocessed Sentaurus Device command file by using the Insert command in the Sentaurus Device command file sdevice des.cmd:

```
Insert= "n@node | Matpar@ extension.cmd"
```

The complete procedure for inserting arbitrary content into the Sentaurus Device command file is illustrated with the following examples.

Example 1: Heterostructure

In Table 6 on page 14, the emitter and base regions contain the statement Recombination (Radiative) in the Extension column. Regionwise Physics statements for emitter and base regions can be inserted in the Sentaurus Device command file by using the following procedure:

- 1. Add Sentaurus Device after the MatPar node in the tool row in the epi project.
- 2. Add this command to the Global section of the Epi command file epi epi.csv:

```
$global append columnNames extension
```

3. Add this code to the MatPar command file MatPar_mpr.cmd after sourcing n@node@ epi.tcl:

```
set FID [open "n@node@_extension.cmd" w]
foreach key [getLayerKeyList "region,*,extension"] {
   loadLayerVariables $key
   puts $FID "Physics(Region=\"$region\") \{$extension\}"
}
close $FID
```

After execution of the MatPar node, if the MatPar node number is 9, MatPar creates the file n9 extension.cmd.

4. Add this line to the Sentaurus Device command file sdevice des.cmd:

```
Insert= "n@node|MatPar@ extension.cmd"
```

5. Preprocess the Sentaurus Workbench project.

The following statement appears in the preprocessed command file:

```
Insert= "n9 extension.cmd"
```

6. Run the Sentaurus Workbench project.

During run-time, Sentaurus Device uses the following regionwise Physics statements:

```
Physics(Region="emitter") {Recombination(Radiative)}
Physics(Region="base") {Recombination(Radiative)}
```

Example 2: Multiple-quantum well structure

To insert regionwise Physics statements for a multiple-quantum well structure shown in Table 11 on page 31:

- 1. Add Sentaurus Device after the MatPar node in the tool row in the epi project.
- 2. Add this command to the Global section of the Epi command file epi epi.csv:

```
$global append columnNames extension
```

3. Add this code to the MatPar command file MatPar_mpr.cmd after sourcing n@node@ epi.tcl:

```
set FID [open "n@node@_extension.cmd" w]
foreach key [getLayerKeyList "region,*,extension"] {
   loadLayerVariables $key
   puts $FID "$extension"
}
close $FID
```

After execution of the MatPar node, if the MatPar node number is 9, MatPar creates the file n9_extension.cmd.

4. Add this line to the Sentaurus Device command file sdevice des.cmd:

```
Insert= "n@node | MatPar@ extension.cmd"
```

5. Preprocess the Sentaurus Workbench project.

The following statement appears in the preprocessed command file:

```
Insert= "n9 extension.cmd"
```

6. Run the Sentaurus Workbench project.

During run-time, Sentaurus Device uses the following regionwise Physics statements:

```
Physics(region=qwell1) {Recombination(-Radiative) Active}
Physics(region=qwell2) {Recombination(-Radiative) Active}
```

Source parameter files

MatPar uses the source parameter files to create the user-defined material parameter files. The names of these files are specified in the Epi command file (see Material and Interface section on page 19).

There are two types of source parameter file:

- The <material>.tcl files are Tcl source parameter files and contain Tcl commands enclosed in a single Tcl command block¹. MatPar processes these files to create the user-defined material parameter files.
- The <material>.par files have the same format as Sentaurus Device parameter files. A <material>.par file can be either a Sentaurus Device default parameter file or a user-defined parameter file created using the Sentaurus Device approach. MatPar includes these files without processing in the user-defined material parameter files.

NOTE There can be only one <material>.tcl and one <material>.par file for each material or region.

All source parameter files reside in the par subdirectory. The material name in the <material>.tcl and <material>.par files follows the standard convention for naming materials. For example, the Tcl source parameter files corresponding to germanium, gallium arsenide, and aluminum gallium arsenide are Ge.tcl, GaAs.tcl, and AlGaAs.tcl.

Tcl source parameter files

All Tcl source parameter files in the Sentaurus Workbench project can be directly accessed from Sentaurus Workbench.

To open all material.tcl files simultaneously in a text editor:

Right-click the MatPar icon in the tool row, and select Edit Input > Edit All material.tcl
 Files.

All material.tcl files are loaded in the text editor, but only one material.tcl file opens in the text editor. The other files are listed in the **File** menu of the editor and are opened by selecting **File** > <path/material.tcl>.

^{1.} A Tcl command block consists of an arbitrary set of Tcl command lines that are delimited by "!(" and ")!" [4].

The Tcl source parameter files have four sections:

- Variable Definition section: Defines the variables material and cbo.
- Input Validation and Header Printing section: Validates the value of variables, and prints the header section in user-defined parameter files.
- Parameter Initialization section: Calculates the model parameter set value for each parameter section.
- Parameter Printing section: Prints the parameter section in user-defined parameter files.

Variable Definition section

The Variable Definition section defines the two variables material and cbo (see Table 15) using the set Tcl command.

Table 15 Variables and procedures used in Variable Definition section

Variable/Procedure	Description
cbo	Conduction-band offset value with respect to reference material for electron affinity.
material	Name of material corresponding to the material.tcl file. Mandatory variable.
<pre>initProperty <material> <pre><pre><pre><pre><pre><pre><pre><pre></pre></pre></pre></pre></pre></pre></pre></pre></material></pre>	This procedure calculates the model parameters for the specified material, parameter section, and model.
<pre>\${material}::<parametersection>:: print</parametersection></pre>	This procedure prints the specified parameter section in the user-defined material parameter file.

The variable cbo is defined if the multilayer stack consists of a heterostructure and if the <material>.tcl file does not correspond to the reference material for electron affinity. For example, for a GaAs/Ge heterostructure, if Ge is the reference material for electron affinity and the cbo of GaAs with respect to Ge is 0.35, the Variable Definition section of GaAs.tcl is:

```
set material GaAs
set cbo 0.35
```

and the Variable Definition section of Ge.tcl is:

```
set material Ge
```

The reference material and cbo are defined in Simulating band structure of heterostructures on page 63.

Input Validation and Header Printing section

This section comprises two mandatory commands:

```
source ../lib/printPar.tcl
printPar::header
```

Paths to all directories and files in the Tcl source parameter file are specified relative to the epi subdirectory. The printPar.tcl file resides in the lib subdirectory. The file PhysicalConstants.tcl is sourced in printPar.tcl and contains the definitions of several fundamental physical constants such as Planck's constant, the speed of light, the Boltzmann constant, and electron charge. It can also be used to define miscellaneous constants such as π . These constants can be referenced from all Tcl source parameter files and model files. These constants are used by some model files to compute material properties.

The file printPar.tcl also validates the value of the physical variables temp, cbo, xMole, and yMole:

- If the device temperature is not defined in MatPar_mpr.cmd or if it is defined to be negative, the project aborts.
- If abo is defined in the Tal source parameter file and is less than 0 or greater than 1, the project aborts.
- For ternaries, xMole is defined in the CSV file of Epi. If xMole is less than 0 or greater than 1, the project aborts.
- For quaternaries, both xMole and yMole are defined in the CSV file. If xMole and yMole are each less than 0 or greater than 1, or if xMole + yMole \neq 1, the project aborts.

The user-defined parameter files consist of a header section followed by several parameter sections. The header section contains values of the variables:

- material
- temp
- substrate
- cbo
- doping
- xMole
- vMole

Of these variables, material, cbo, doping, xMole, and yMole are defined for each layer in the CSV file of Epi.

The variables temp and substrate are defined for the complete device in MatPar_mpr.cmd. If any of these variables is not defined, the string "--" is printed as the value of the variable in the header section.

The following is an example of the header section for a user-defined GaAs parameter file corresponding to a GaAs layer with doping concentration of 1×10^{18} cm⁻³:

```
**********

* Material parameter file for GaAs

* Temperature : 300 [K]

* Substrate : --

* conduction band offset ratio: -- [1]

* Doping concentration : 1e18 [cm-3]

* Mole fraction x : -- [1]

* Mole fraction y : -- [1]
```

For the doping and x-mole fraction profiles, the default value is printed. All lines in the header section are commented out in the user-defined parameter file.

Print procedures

The file printPar.tcl contains procedures for printing the header section and various parameter sections in the user-defined parameter files. All procedures are defined in the namespace printPar in the file printPar.tcl.

To print the header section, use the procedure:

```
printPar::header
```

To print the parameter section, use the procedure:

```
printPar::<ParameterSection>Section
```

For example, to print the Epsilon section in the user-defined parameter file, use:

```
printPar::EpsilonSection
```

Table 13 on page 42 lists the names of all parameter sections for which a print procedure is defined in printPar.tcl and the name of the print procedure for each parameter section.

Some models offer a choice between different representations or formulas for the same (or equivalent) physical parameters, for example, effective mass or density-of-states. A particular representation is selected by using the parameter Formula [2]. In such cases, the model parameter set of a particular parameter section and, therefore, the name of the print procedure is different for different formulas.

For example, the procedure printPar::HighFieldDependenceTEM2Section prints the HighFieldDependence parameter section with model parameters for the transferred electron model and the velocity saturation model corresponding to Model 2 [2].

Parameter Initialization section and Parameter Printing section

The Parameter Initialization section consists of a group of initProperty statements, followed by the Parameter Printing section, which contains a group of print procedures. There is exactly one initProperty statement and one corresponding print procedure for each parameter section to be printed in the parameter file:

```
initProperty <material>  propertyGroup> <parameterSection> <model>
${material}::<parameterSection>::print
```

Printing a particular parameter section in a user-defined parameter file requires two main steps:

- 1. Computing the model parameter set value.
- 2. Printing the parameter section along with the computed value of the model parameters in the user-defined parameter file.

The execution of the initProperty statement in a Tcl source parameter file initiates Step 1; whereas, the execution of the print statement in the Tcl source parameter file initiates Step 2 as discussed below.

The initProperty procedure sources the file pardb/<material>/parameterSection>/<model>.tcl and:

- The model parameter set for the corresponding parameter section is computed in the namespace \${material}::<parameterSection>.
- The procedure for printing the parameter section, print, which is defined in the namespace \${material}::<parameterSection> in the <model>.tcl file, is initialized.

The procedure \${material}::<parameterSection>::print prints the parameter section along with the computed value of the model parameters as follows:

- Executing \${material}::<parameterSection>::print invokes the print procedure
 defined in the namespace \${material}::<parameterSection> in the model file.
 Usually, this print procedure is called printPar::<ParameterSection>Section.
- Executing printPar::<ParameterSection>Section from the <model>.tcl file invokes the <ParameterSection>Section procedure in the printPar namespace defined in the printPar.tcl file, which finally prints the parameter section along with the computed model parameter set in the user-defined parameter file.

For example, the statements:

```
set material GaAs
initProperty GaAs BandStructure Bandgap Levinshtein
${material}::Bandgap::print
```

calculate the Levinshtein parameter set for the GaAs Bandgap section and print the Bandgap section in the user-defined GaAs parameter file using the procedure GaAs::Bandgap::print. The procedure GaAs::Bandgap::print invokes the procedure printPar::BandgapSection, defined in printPar.tcl.

NOTE In the case of <material>.par source parameter files, the <material>.par file contains the value of model parameters for all parameter sections. The source parameter file is included as is in the user-defined materialwise parameter file.

Using parameter sections in Tcl source parameter files

Instead of using a pair of initProperty and print statements to print parameter sections in a user-defined parameter file, you can explicitly add the parameter section outside the Tcl command block in a Tcl source parameter file. The parameter section is printed as is in the user-defined parameter file. For example, the following listing in the GaAs.tcl file prints both the Bandgap and Epsilon sections:

As explained in Run-time and preprocessed models on page 67, for regions with doping or mole-fraction profiles, the parameter section for the default models must be included explicitly in the Tcl source parameter file. This ensures that Sentaurus Device computes the correct material property values during run-time.

NOTE Doping, mole-fraction, and temperature profiles are not supported for new models.

Template Tcl source parameter file

The epi/par subdirectory includes a template file material_template.tcl, which includes all of the abovementioned sections of the Tcl source parameter file. It contains initProperty statements and calls to print procedures for all parameter sections for which a print procedure is defined in printPar.tcl (see Table 13 on page 42).

You can use the material_template.tcl file as a template to create a customized Tcl source parameter file, <material>.tcl, for any material by replacing all instances of <...> in material template.tcl with the appropriate numbers or character strings.

The following list shows part of the material template.tcl file:

```
set material <material>
set cbo <cbo>
source ../lib/printPar.tcl
printPar::header
initProperty $material Permittivity Epsilon <model>
${material}::Epsilon::print
```

Model files

A particular model file in the Material Parameter Database corresponds to a particular material property model with a model parameter set value. All model files are Tcl script files.

A model file:

- Implements a default model or a new model.
- Computes the model parameter set corresponding to the default model for a particular parameter section and material.
- Defines the print procedure for the corresponding parameter section.

Some model files also compute the relevant material property in order to print it in the userdefined parameter file and to visualize its variation as a function of a physical variable in the Material Parameter Plotter.

Model types and naming model files

The name of model files in the Material Parameter Database has the general format <model>.tcl, where model is the name of the model file. The guidelines used to name the model files in the Material Parameter Database are presented here. As discussed in Material

Parameter Database on page 41, model files are located in the Material Parameter Database in the directory cparameterSection:

pardb/<material>//croup>/<parameterSection>/<model>.tcl

The following model types are implemented in the model files:

- Equation-based models where the dependency of a material property on physical variables is expressed in terms of equations.
- *Table-based* models where the dependency of a material property on a particular physical variable is expressed in terms of tabular data.

For example, the Jain–Roulston bandgap narrowing model is an equation-based model, and the TableBGN bandgap narrowing model is a table-based model.

In the literature of compound semiconductors, for a particular material property of a material:

- Various authors have published different values for the parameter set of a particular model.
- Different models exist.

Both of these possibilities can be implemented in the model files. The model parameter set for a particular parameter section of the material parameter file corresponds to the default model for the corresponding material property and is called the *default parameter set*. All model files compute a value for this default parameter set. A particular model file implements one of the following model types:

- A *default model* for a particular material property is a model that has been implemented in Sentaurus Device. If a model file corresponding to the default model computes the default model parameter set using values from the default material parameter file, the model file is called Default.tcl.
 - If the default model parameter set is computed using the value of the default model parameter set from another source, the model file is named after the first author of the reference: <FirstAuthor>.tcl. For example, the model file Default.tcl in the Bandgap folder for GaAs computes the default model parameter set using the parameter set from the Bandgap section of the default parameter file. The model file Lautenschlager.tcl in the same folder computes the default model parameter set from the model parameter set from Lautenschlager [5]. For details, see Examples of model implementation on page 65.
- A *new model* for a particular material property is a model that has not been implemented in Sentaurus Device. In this case, the new model parameter set is not the same as the default model parameter set. A model file for a new model implements the new model and computes the default model parameter set in terms of the model parameters of the new model. For example, the model file Passler.tcl in the Bandgap folder for GaAs computes the default model parameter set using model parameter set from Pässler [6]. For details, see Examples of model implementation on page 65.

If a particular reference discusses different models for a particular material property and material, the model file names can be <FirstAuthor>-<modelname>.tcl. If a reference discusses only one model, the corresponding model file can be <FirstAuthor>.tcl.

For a few properties, the parameter section can contain different parameter sets depending on the choice of submodels. In such a case, the model file can be named with an appropriate combination of the model names. For example, the HighFieldDependence section corresponds to the high-field mobility models and contains different parameter sets depending on the choice of various submodels. The name of the model file that implements the default transferred electron model with the velocity saturation model called Model 2 is Default-TEM2.tcl.

In addition, you can implement some equation-based default models in terms of table-based models. For example, the Jain–Roulston model for GaAs has been implemented in the form of a table-based model, and the model file is:

```
pardb/GaAs/Bandgap/TableBGN/Default-JainRoulston.tcl
```

For some material properties, multiple models are implemented in Sentaurus Device, that is, there are multiple default models. In such cases, there can be more than one way of implementing a new model using the default models. In this case, the model file name is <FirstAuthor>-<DefaultModel>.tcl.

For example, the Arora and Masetti models are examples of doping-dependent mobility models. They are also default models since they are implemented in Sentaurus Device. The mobility model discussed in a paper by Sotoodeh has been implemented for GaAs in the Material Parameter Database in terms of both the Arora model and the Masetti model, and the model files are called Sotoodeh-Arora.tcl and Sotoodeh-Masetti.tcl, respectively.

Sections of model file

The computation of the default model parameter set as well as the printing of the parameter sections are through Tcl commands.

A model file contains:

- A header section, which is used to document the model.
- A model implementation and printing section, which is used to compute the default model parameter set and to define or invoke the print procedure for the parameter section in the user-defined parameter file.

Header section

The header section contains several fields for documentation purposes (see Table 16). Most fields can be accessed in the documentation of the Material Parameter Database. Each line in the header section begins with #!. A field and its content can be written in either of the following ways:

• A line contains the field name, followed by the field content. For example:

```
#! <Field>: <Content of the field>
```

• A line contains the field name, followed by the field content on subsequent lines. For example:

```
#! <Field>:
#! <Content of the field>
#! <Content of the field>
```

Table 16 Fields in header section of model file

Field	Description
CALCULATED PARAMETER	Calculated parameters or material property or both.
EXPRESSION	Equation used to calculate the model parameters or material property or both.
MATERIAL	Name of the material.
MODEL	Brief description of the model.
NOTES	Recommendations on using the model or further explanation of the model.
PROPERTY	Name of the material property corresponding to the parameter section.
REFERENCE	Source of the model.
SDEVICE	Syntax for activating the model in Sentaurus Device. This field is empty if the model does not require explicit activation.
VALIDITY	Conditions under which the model is valid. If the reference does not specify the validity, this field is empty.

By default, there is no empty line in the HTML documentation of the content of the field. If there are several lines of content, the documentation can be made more readable by adding on a separate line between two lines of content.

As a result, an empty line is inserted between the two subsequent lines. For example, as a result of the following header section, an empty line is inserted in the documentation between the lines starting with Temperature and Eg(T):

```
#! EXPRESSION
#! Temperature-dependent band gap is calculated using
#! #! #! Eg(T) = Eg0 + alpha*Tpar^2/(Tpar + beta) - alpha*T/(T + beta)
```

Some models in Sentaurus Device are activated by a specific command in the Sentaurus Device command file. The SDEVICE field specifies the syntax of this command. If the model does not need to be activated, this field is empty.

Model implementation and printing section

The model implementation and printing section is used to calculate the default model parameter set and material property, and to define the print procedure to be used for the parameter section in the user-defined parameter file. It contains the namespace <material>::ematerial>::cmaterial>::cmaterial>: in which two procedures init and print are defined. For example, all model files that compute the model parameter set for the Bandgap section define init and print procedures in the namespace GaAs::Bandgap.

The calculation of the model parameter set is implemented in the init procedure, which returns the default model parameter set and, for some parameter sections, the value of the relevant material property.

Sentaurus Device uses the default model and the default model parameter set values to calculate the value of the relevant material property. In addition to this, the calculation of material property value is implemented in some model files for the purpose of printing it in a commented line in the parameter section.

For such parameter sections, the value of the material property can be obtained without performing the device simulation. In addition, these material properties can be plotted using the Material Parameter Plotter. All model parameters and property values to be printed in the user-defined parameter file must be declared using the Tcl command variable:

```
variable <modelParameter>
variable <materialProperty>
```

For example, in the GaAs::Bandgap namespace, the default model parameter set and the material property are declared using the variable command as follows:

```
# Default model parameter set
variable alpha
variable beta
variable Tpar
variable Eg0
variable Bgn2Chi
variable Chi0
# Material properties
variable Chi
variable Eg
```

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Epi/MatPar User Guide April 2008 The value of these parameters is computed in the rest of the code in the corresponding model file.

The print procedure contains a single statement of the form:

```
printPar::<ParameterSection>Section
```

This invokes the appropriate procedure for printing the parameter sections, which are defined in printPar.tcl.

The last line of the model file executes the init procedure in the namespace <material>::<material>::

```
<material>::<parameterSection>::init
```

When a model file is sourced through a call to the initProperty procedure, the execution of the last line in the model file results in the computation of the default model parameter set. When the print procedure is executed in the Tcl source parameter file, it invokes the print procedure in the namespace <material>::executed:executedin the parameter section>, which then prints the parameter section.

Simulating band structure of heterostructures

Sentaurus Device uses the electron affinity model [7] to calculate the band diagram of a heterostructure. According to this model, the conduction-band discontinuity (CBO) between the two semiconductors in a heterostructure is given by:

$$\Delta E_{\rm C} = -\Delta \chi \tag{2}$$

and the valence-band discontinuity (VBO) is given by:

$$\Delta E_{\rm V} = \Delta E_{\rm g} - \Delta E_{\rm C} \tag{3}$$

where:

- \bullet χ is electron affinity of a material.
- $E_{\mathfrak{g}}$ is the band gap of a material.
- $E_{\rm C}$ is the conduction-band edge, $E_{\rm V}$ is the valence-band edge, and ΔE denotes the difference in these energies.

Sentaurus Device uses the electron affinity (Chio) and bandgap (Ego) values of the materials from the Bandgap section in the corresponding material parameter files of the materials in the heterostructure.

Experimental measurements of the band discontinuities in a heterostructure may differ from the values obtained from the electron affinity model. In this case, to simulate the correct band diagram of the heterostructure, one of the materials is chosen as a reference material, and the electron affinity value of the other material is modified using:

$$\chi = \chi_{\text{ref}} - \Delta E_{\text{C}}(\text{measured}) \tag{4}$$

where χ_{ref} is the electron affinity of the reference material, and χ is the electron affinity of the other material. To simulate the correct band diagram, the value of Chi0 in the reference material parameter file is not changed; whereas, the value of Chi0 in the material parameter file of the other material is modified to the value obtained from Eq. 4.

For many heterostructures, experimental measurements of the conduction-band offset (cbo) or valence-band offset (vbo) are available. The cbo is defined as:

$$cbo = \frac{\Delta E_{\rm C}}{\Delta E_{\rm o}} \tag{5}$$

and the vbo is defined as:

$$vbo = \frac{\Delta E_{V}}{\Delta E_{g}}$$
 (6)

If the cbo is known, the electron affinity of one of the materials in the heterostructure is modified to:

$$\chi = \chi_{\text{ref}} - \text{cbo} \bullet (E_{g} - E_{g,\text{ref}}) \tag{7}$$

where $E_{\rm g}$ and $E_{\rm g,ref}$ are the band gaps of the material and reference material, respectively. Again, it is assumed that the electron affinity model is valid.

In the MatPar approach, the reference material is defined in the MatPar command file using the Tcl variable substrate, and the cbo value of a material is defined using the Tcl variable cbo in the Tcl source parameter file of the corresponding material.

In the Material Parameter Database, all of the model files in the Bandgap folder calculate the value of the band gap and the electron affinity for a material. This value of the electron affinity can be called the *unmodified electron affinity* of the material.

If a reference material is defined and the cbo value for a particular material is defined, the model file (which is used to calculate the model parameters of the Bandgap section) for the material calculates the modified value of Chi using Eq. 7. MatPar prints this modified value of the electron affinity in the corresponding user-defined parameter file.

For simulations involving heterostructures with more than two types of material, the electron affinity (χ) of each material in the multilayer stack is calculated with respect to the electron affinity of the reference material using Eq. 7. Similar to the case of a multilayer stack consisting of only two materials, in the MatPar approach, you must specify the reference material in the MatPar command file and the cbo of each material with respect to the reference material in the corresponding Tcl source parameter files.

When using MatPar, if you do not define substrate and cbo, Sentaurus Device uses the bandgap values and unmodified electron affinity values to simulate the heterostructure band diagram.

If the experimental values of vbo, CBO, or VBO are available, instead of specifying cbo in the Tcl source parameter file, vbo, CBO, or VBO can be specified; and the corresponding model file of the material can be modified accordingly to calculate the modified value of Chi using equations similar to Eq. 4 or Eq. 7.

Examples of model implementation

These examples illustrate model implementation for both default models and new models.

Implementing default bandgap model

The Varshni bandgap model (Eq. 1, p. 37) is the default bandgap model. Therefore, the Varshni bandgap model parameter set is the default model parameter set. The default model parameter set {Eg(0), Chi(0), alpha, beta, Tpar, Bgn2Chi} is defined in the GaAs bandgap default model file (pardb/GaAs/BandStructure/Bandgap/Default.tcl) using the Tcl variables {Eg0, Chi0, alpha, beta, Tpar, Bgn2Chi}:

```
variable alpha 5.4050e-04
variable beta 2.0400e+02
variable Tpar 0.0
variable Eg0 1.519
variable Bqn2Chi 0.5
```

The value defined above for each parameter is from the Bandgap section of the default material parameter file for GaAs. If the Tcl variables substrate and cbo are defined, the value of Chi for GaAs is calculated using Eq. 7, followed by the calculation of the value of Chi0. Otherwise, the default value of Chi0 is used, followed by the calculation of Chi:

```
variable Chi0 4.07
variable Chi [expr {$Chi0 - $alpha*$Tpar*$Tpar/(2*($Tpar + $beta)) +
$alpha*$::temp*$::temp/(2*($::temp + $beta))}]
```

In addition to the default model parameter set, this model file calculates the band gap Eg (using Eq. 1, p. 37) and the electron affinity Chi at temperature temp:

```
variable Eg [expr {$Eg0 + $alpha*$Tpar*$Tpar/($Tpar + $beta) -
$alpha*$::temp*$::temp + $beta)}]
```

Even though both Eg and Chi are not required for the Bandgap section, the default model file calculates these material properties for:

- Printing these values in commented lines in the Bandgap section.
- Plotting using the Material Parameter Plotter.

Implementing Lautenschlager bandgap model

The Lautenschlager bandgap model [8] is the same as the Sentaurus Device default model. The model file pardb/GaAs/BandStructure/Bandgap/Lautenschlager.tcl implements the calculation of the default model parameter set, using the Varshni model parameter set from Lautenschlager.

Since Lautenschlager does not mention any parameter values for Chi0 and Bgn2Chi, the default model parameter values are used for these parameters:

```
# Parameters from Lautenschlager
variable alpha 5.5000e-04
variable beta 2.2500e+02
variable Tpar 0.0
# Parameters from default model parameter set
variable Eg0 1.517
variable Bgn2Chi 0.5
```

The values of Chi and Chi0 are calculated as in Implementing default bandgap model on page 65.

Implementing Pässler bandgap model

The Pässler model [6] expresses the temperature dependency of band gap using:

$$E_{g}(T) = E_{g}(0) - \frac{\alpha\Theta}{2} \left[p \sqrt{1 + \left\langle \frac{2T}{\Theta} \right\rangle^{p}} - 1 \right]$$
 (8)

where $E_{\rm g}(0)$, α , p, and Θ are parameters. The Pässler model parameter set $\{E_{\rm g}(0), \alpha, p, \Theta\}$ is represented by the Tcl variables $\{E_{\rm g}(0), \alpha, p, \pm 1\}$ in the Pässler model file.

The Pässler model is implemented by calculating the default model parameter set in terms of the Pässler model parameter set as follows:

```
# Parameters from Passler
set p 2.44
set a 0.472e-3
set theta 230.00
set Eg00 1.519

# Calculate default model parameter set in terms of Passler model parameters
variable alpha 0.0
variable beta 1e-5
variable Tpar 0.0
variable Bgn2Chi 0.5
variable Eg0 [expr {$Eg00 - ($a*$theta/2)*(pow(1.00+pow((2*$::temp/$theta),
$p), 1.00/$p)-1)}]
```

where Eg0 is the value of the band gap calculated from the Pässler model for a particular temperature temp. By defining alpha=0 and beta=0, the temperature dependency of Eg is suppressed in the Varshni model for Sentaurus Device calculation, that is, Eg0=Eg. The temperature dependency is taken into account by calculating the band gap using the Pässler model and setting Eg0 to this value.

Since the Pässler model does not define any value for Chi0, a value from another reference can be used. In Passler.tcl, the electron affinity value at room temperature, Chi300, from Piprek [9] is used to calculate Chi0 and Chi:

```
# Parameters from Piprek
variable Chi300 4.07
variable Chi0 [expr {$Chi300 - $alpha*300.0*300.0/(2*(300.0 + $beta))}]
variable Chi [expr {$Chi0 - $alpha*$Tpar*$Tpar/(2*($Tpar + $beta)) +
$alpha*$::temp*$::temp/(2*($::temp + $beta))}]
```

Run-time and preprocessed models

Several Sentaurus Device default models and the corresponding model parameters depend on the local values of structure parameters (such as local values of the doping concentration or mole-fraction profiles) or solution variables (such as the local values of the lattice or carrier temperature). For such models, the actual value of the model parameters can only be evaluated at run-time¹.

^{1.} As mentioned in Model implementation and printing section on page 62, the material property is also calculated in many of the model files corresponding to the default models for the purpose of printing in the user-defined parameter file or plotting with the Material Parameter Plotter.

NOTE

It is recommended to rely on the built-in default models if the dependency of the model parameters on local or solution fields or both is important. Since the default model parameters are used to compute the material properties during run-time, the default models are also called run-time models.

Often, however, the model parameters do not need to depend on local or solution fields or both. Examples are layers with constant doping and mole fractions as well as isothermal simulations. In such cases, you can compute all model parameters before starting the actual simulation (that is, at a preprocessing stage). This additional flexibility and the MatPar approach are based on preprocessing model parameters, based on regionwise predefined doping and mole-fraction values (defined in Epi) and global parameters such as the temperature.

The new models are implemented in terms of the default models. For example, as discussed in Implementing Pässler bandgap model on page 66, the Pässler bandgap model is implemented in terms of the Varshni bandgap model, which is the default bandgap model. In such cases, the material parameter values of the default model parameter set are computed so that:

- The material property as a function of physical variables is calculated in the model file and is set equal to one of the default material parameters of the corresponding default model.
- A few parameters in the default parameter set are set to zero in the model file, so that the dependency of the material property on the physical variables is suppressed during runtime and, as far as Sentaurus Device is concerned, these material properties are independent of the physical variables.

The new models are also called preprocessed models since the values of material properties computed by the corresponding model files are used by Sentaurus Device during run-time instead of the values computed during run-time. As a result, even though the doping, mole fraction, or temperature may vary as a function of position in a device or may depend on the applied bias, the material property is constant. Therefore, the simulation of devices containing profiles of the physical variables does not give correct results if the new models are used.

For example, the Varshni model is the default bandgap model and {Chi0, Bgn2Chi, Eg0, alpha, beta, Tpar} is the corresponding default model parameter set. The Pässler bandgap model, which is a new model, has been implemented for some materials (for example, GaAs) in the Material Parameter Database.

In the model file Passler.tcl, the band gap and electron affinity are calculated as a function of temperature and are set equal to Ego and Chio, respectively. alpha and beta are set equal to zero. When Sentaurus Device calculates the band gap as a function of temperature during run-time, the band gap is constant throughout the device, even if the temperature varies at different positions inside the device.

For devices containing regions with doping and x-mole fraction profiles, a default reference value for the corresponding variables is specified (see Creating user-defined parameter files for

regions with doping/mole-fraction profiles on page 29). In addition, as discussed in Using parameter sections in Tcl source parameter files on page 57, parameter sections can be explicitly inserted into the Tcl source parameter files, especially for regions with mole-fraction profiles.

Helper procedures for calculating model parameters/ material properties

Table 17 describes some helper procedures in the lib/helper.tcl file. These procedures are helpful in computing model parameters or material properties in the model files.

Table 17 Procedures in helper.tcl

Procedure	Description
readTable <file> <tabletype></tabletype></file>	Reads tabular data from data file <file>, and returns the column values in individual lists.</file>
<tabletype>=<tableodb tablebgn="" =""></tableodb></tabletype>	Controls the variable lists returned by readTable. If tableType=TableODB, readTable returns three lists: wavelength [µm], refractive index [1], and extinction coefficient [1]. The data files contain three columns, one for each of these variables. The columns are separated by blank spaces. If tableType=TableBGN, readTable returns two lists: doping concentration [cm ⁻³] and bandgap reduction [eV]. The data files contain two comma-separated columns for these variables.
linspace <min> <max> <n></n></max></min>	Creates a list of N linearly spaced numbers between min and max (including min and max). linspace is usually used for temperature and mole fraction. N, min, and max have these constraints: N should be greater than 1. min != max. min < max.
logspace <min> <max> <n></n></max></min>	Creates a list of N logarithmically spaced numbers between min and max (including min and max). logspace is used for doping concentration. N, min, and max have these constraints: N should be greater than 1. min != max. min < max. min > 0 and max > 0.

4: Using MatPar

Helper procedures for calculating model parameters/material properties

Table 17 Procedures in helper.tcl

Procedure	Description
decadelinspace <min> <max> <n></n></max></min>	Creates a list of linearly spaced numbers between each decade interval specified using min and max. There are N numbers in each decade interval. The generated list contains 2N - 1 numbers. decadelinspace is used for doping concentration. N, min, and max have these constraints: N should be greater than 1. min != max. min < max. min < 0 and max > 0.
maxima <list_of_numbers></list_of_numbers>	Finds the maxima in a list of numbers.
<pre>maxIndex <list_of_numbers></list_of_numbers></pre>	Finds the maxima in a list of numbers and the index corresponding to the maxima.
minima <list_of_numbers></list_of_numbers>	Finds the minima in a list of numbers.
minIndex <list_of_numbers></list_of_numbers>	Finds the minima in a list of numbers and the index corresponding to the minima.

The model files for the parameter sections TableODB and TableBGN implement table-based models. These model files read the columnar data in the data files stored in a subdirectory and store the data as separate lists. Generally, one list is created for each data column. This is accomplished by using the readTable procedure.

For example, the Levinshtein model for TableODB (pardb/GaAs/Optics/TableODB/Levinshtein.tcl) and the default model for TableBGN (pardb/GaAs/BandStructure/TableBGN/Default.tcl) use the readTable procedure.

The procedures linspace, logspace, and decadelinspace are useful for generating lists of numbers. They generate lists of physical variables such as doping concentration, temperature, and mole fraction. These procedures are used in model files as well as the command file of the Material Parameter Plotter. For example, the command:

```
linspace 200 300 11
```

generates a list of 11 linearly spaced temperature values between 200 and 300:

The command:

logspace 1e15 1e16 10

generates a list of ten logarithmically spaced doping concentration values between 1e15 and 1e16:

```
1e15, 1.2915e+15, 1.6681e+15, 2.1544e+15, 2.7826e+15, 3.5938e+15, 4.6416e+15, 5.9948e+15, 7.7426e+15, 1e16
```

The procedure decadelinspace generates a linearly spaced list of numbers in a decade interval. For example, the commands:

```
decadelinspace 1e15 1e16 10 decadelinspace 1e16 1e17 10
```

generate ten linearly spaced doping concentration values between 1e15 and 1e16, and another ten values between 1e16 and 1e17:

```
1e15, 2e15, 3e15, ..., 9e15, 1e16
1e16, 2e16, 3e16, ..., 9e16, 1e17
```

The command:

```
decadelinspace 1e15 1e17 10
```

generates a list of 19 numbers:

```
1e15, 2e15, 3e15, ..., 9e15, 1e16, 2e16, 3e16, ..., 9e16, 1e17
```

The file pardb/GaAs/BandStructure/TableBGN/Blieske.tcl uses the procedure decadelinspace to generate a list of doping concentration values and to calculate bandgap narrowing.

The procedure minima returns the minima of a list of numbers, and minIndex returns the minima as well as the index of the minima in the list. For example:

```
minIndex {4 8 7 5 9 1 8}
```

results in:

1 5

The model file pardb/AlGaAs/Bandgap/Levinshtein.tcl uses minIndex to calculate the GaAs band gap as the minima of band gaps of the Γ -, L-, and X-bands.

Interpolation procedures for ternary and quaternary compound semiconductors

Material parameters of ternary alloys are calculated by interpolating the material parameters of binary compounds. Similarly, for quaternary alloys, material parameters of binary or ternary semiconductors are used.

The interpolation equations discussed in [2][9][10] are implemented in several procedures in the compound library file lib/compound_lib.tcl. Table 18 lists these procedures. Here, the material parameter can be a material property (for example, a dielectric constant) or a model parameter (for example, Eg0 and Chi0).

Table 18 Interpolation procedures in compound_lib.tcl

Procedure	Description
compute_ternary x AB BC K	Returns the ternary alloy A (x) B (1-x) C material parameter by an interpolation between the binary semiconductor parameters AB and BC. K is the bowing parameter. P (A (x) B (1-x) C) = AB*x+BC* (1-x) -K*x* (1-x) [9]. By default, K=0.
compute_2_2_quaternary x y ABC ABD BCD ACD	Returns the quaternary alloy A $(1-x)$ B (x) C (y) D $(1-y)$ material parameter from an interpolation between the ternary alloy parameters: ABC, ABD, BCD, and ACD. V $(A(1-x)$ B (x) C (y) D $(1-y)$ $) = (x*(1-x)*(y*ABC+(1-y)*ABD) + y*(1-y)*(x*BCD+(1-x)*ACD)) / (x*(1-x)+y*(1-y))$ [2]
comp_3_1_QB x y AD BD CD k_ABD k_ACD k_BCD	Returns the quaternary alloy A (x) B (y) C (1-x-y) D material parameter from an interpolation between the binary alloy parameters: AD, BD, and CD, with bowing parameters for the ternaries k_ABD , k_ACD , and k_BCD . By default, $k=0$.
comp_quaternary x y B1 B2 B3 B4 C12 C14 C23 C34 D	Returns the quaternary alloy material parameter from a second-order interpolation between the binary alloys B1, B2, and B3, and B4, with bowing parameters of the ternary alloys C12, C14, C23, and C34, and the quaternary bowing parameter D. The interpolation formula can be expressed as an inner product with a 3 x 3 matrix for the alloy parameters [10].

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How MatPar creates user-defined parameter files

MatPar utilizes the user-specified inputs (MatPar command file, source parameter files, and model files) to create the user-defined parameter files for a multilayer stack as follows:

- The MatPar node is executed, and the commands in the MatPar command file (MatPar mpr.cmd) are executed.
- Information about the layered structure is loaded into MatPar by sourcing n@node@_epi.tcl through the MatPar command file. This includes the following information relevant for the creation of a user-defined parameter file:
 - Doping and mole fraction of each layer.
 - Source parameter file for each layer for creating user-defined regionwise parameter files
 - parFileMask value for determining the names of user-defined regionwise parameter files.
 - Source parameter files for creating materialwise parameter files.
- The following variables are defined using appropriate commands in the MatPar command file:
 - Variables relevant for the complete device structure, for example, temperature and wavelength.
 - Location of the parameter database directory pardb.
- For each layer, MatPar determines the names of the user-defined regionwise and materialwise parameter files to be created. It also determines the names of the source parameter files used for creating these parameter files.
- MatPar processes each source parameter file sequentially to create the user-defined parameter files (see Order in which MatPar processes source parameter files on page 24).
 - If the source parameter file is a material.par file, the user-defined parameter file is a copy of the source parameter file. If it is a Tcl source parameter file, MatPar processes it to compute the default model parameter set and to print the parameter sections in a user-defined parameter file.

Each Tcl source parameter file is processed as described here:

- Variables that represent layer properties such as material and cbo are defined.
- The model parameter set is calculated by executing initProperty procedures and sourcing model files: The parameter section to be printed and the model to be used for printing the parameter section are specified in an initProperty statement. The format of the initProperty statement is:

initProperty <material> propertyGroup> <parameterSection> <model>

The arguments to the initProperty procedure are also used to build the path of the model file. The path of the model file is:

```
pardb/<material>//croup>/<parameterSection>/<model>.tcl
```

The default model parameter set is calculated by sourcing the model file. The parameters are calculated in the namespace material::parameterSection, which is defined in the model file. For example, to print the GaAs bandgap parameter section using model parameters from the Levinshtein model, the following initProperty statement must be specified:

initProperty GaAs BandStructure Bandgap Levinshtein

The model parameters Chi0, Eg0, alpha, beta, and Tpar are calculated by sourcing the Levinshtein model file pardb/GaAs/BandStructure/Bandgap/Levinshtein.tcl. These model parameters are calculated in the namespace GaAs::Bandgap.

■ Parameter sections are printed by executing print procedures: In a Tcl source parameter file, for every initProperty statement, there is a print statement that prints the parameter section along with the computed model parameter set in the user-defined parameter file. The print procedure is defined in the lib/printPar.tcl file, and it has the name printPar::parameterSection>. This procedure is called from the namespace <material>::print (defined in the model file), which is called by the statement <material>::cparameterSection>::print from the Tcl source parameter file <material>.tcl.

For example, to print the GaAs Bandgap section using the model parameters from Levinshtein, the procedure GaAs::Bandgap::print from GaAs.tcl calls the procedure printPar::BandgapSection through the file pardb/GaAs/BandStructure/Bandgap/Levinshtein.tcl.

Material Parameter Plotter

The Material Parameter Plotter is an Inspect-based utility for plotting the variation of material parameters (material property as well as model parameters) as a function of the physical variables such as doping concentration, temperature, mole fraction, and wavelength. It can visualize:

- The variation of a material property as a function of physical variables for multiple models. For example, the temperature variation of the GaAs band gap for multiple models such as Levinshtein, default, and Pässler can be plotted.
- The variation of auxiliary material properties as a function of physical variables. An auxiliary material property is a property that is calculated from the material properties computed from model files in the Material Parameter Database. The auxiliary material properties are not defined in Sentaurus Device. For example, lifetime and doping-dependent mobility can be computed from the model files and can be used to calculate the

- diffusion length. The diffusion length can be plotted as a function of doping concentration for multiple models.
- Equation-based models and table-based models. For example, the refractive index and extinction coefficient can be plotted as a function of wavelength from models for the TableODB section of the parameter file.

The Material Parameter Plotter uses Inspect, a user-specified Inspect command file, several helper procedures defined in lib/helper.tcl and pardb/mprPlotter/computematpar.tcl, and model files in the Material Parameter Database.

The Material Parameter Plotter is located in the pardb directory as a Sentaurus Workbench project called mprPlotter. The mprPlotter project comprises several instances of Inspect. Each Inspect instance has a command file that contains commands for plotting the material properties using Inspect. The collection of all Inspect instances in mprPlotter forms the example library of the Material Parameter Plotter (see Example library on page 80).

Each instance of Inspect demonstrates the use of a combination of Tcl, Material Parameter Plotter, and Inspect commands to plot material properties as a function of physical variables and is a use example of the Material Parameter Plotter. For example, the Inspect instance identified by the tool name Egvst demonstrates the use of the Material Parameter Plotter to plot band gap as a function of temperature.

Command file

The default command file name for Inspect is <code>inspect_ins.cmd</code>. The command file uses standard Tcl commands, Material Parameter Plotter commands, and Inspect commands to compute and plot the curves in Inspect.

Properties from both equation-based and table-based models can be plotted as a function of the physical variables such as doping concentration, temperature, x-mole fraction, y-mole fraction, and wavelength of incident light.

The Material Parameter Plotter commands consist of the following Tcl procedures:

- getDataFromEqn
- getXdataFromTable
- getYdataFromTable

These procedures are defined in pardb/mprPlotter/computematpar.tcl (see Table 19).

Table 19 Procedures defined in computematpar.tcl

Procedure	Description
getDataFromEqn <xdata></xdata>	Returns a list of computed <ydata> from a list of <xdata>. Calculates a list of physical property values (<ydata>) from equation-based models. <xdata> is the list of physical variable values used to calculate <ydata>.</ydata></xdata></ydata></xdata></ydata>
getXdataFromTable	Returns a list of <xdata>. Used for table-based models.</xdata>
getYdataFromTable	Returns a list of <ydata>. Used for table-based models.</ydata>

The Material Parameter Plotter uses model information and physical variable information to compute the physical property. The Material Parameter Plotter commands are used to compute the physical property and to store the values of the physical variable and physical property in two separate lists. The Material Parameter Plotter uses the Inspect commands cv_createFromScript and cv_display to create a curve and to display the curve in Inspect [11]. In general, all Tcl variables are defined in the global namespace in the command file of the Material Parameter Plotter.

Plotting and displaying a single curve in Inspect

To create and display a single Inspect curve, follow the sections here.

Specifying path of pardb directory and source library files

The Material Parameter Plotter uses helper procedures (lib/helper.tcl) and model files from the pardb directory, as well as procedures defined in pardb/mprPlotter/computematpar.tcl (see Table 19).

To specify the path of the pardb directory, use the Tcl command:

```
set ::pardb <path_to_epi_directory>
```

The paths of all directories and files in the Material Parameter Plotter command file are specified relative to the mprPlotter directory. In addition, the Tcl variable pardb is defined in the global namespace of the Tcl interpreter. The library files are sourced using:

```
source ../../lib/helper.tcl
source computematpar.tcl
```

Defining model and material property

The model is defined by specifying the Tcl variables material, propertyGroup, parSection, and model in the global namespace:

```
set ::material <material_Name>
set ::propertyGroup propertyGroup_Name>
set ::parSection cparameterSection Name>
```

The names of the property group and parameter section are described in Table 13 on page 42. The Material Parameter Plotter uses the above Tcl variables to locate the model file, specified by:

```
set ::model <model name>
```

The material property or model parameter of interest is specified by:

where:

The model file returns the value of this variable to the Material Parameter Plotter. It is usually plotted on the y-axis in Inspect. The propertyVariable_Name can be found in the CALCULATED PARAMETER field of the documentation on model files (see Table 16 on page 61). As discussed in Model implementation and printing section on page 62, these are specified in the model files using the syntax:

```
variable propertyVariable Name>
```

For example, the default GaAs bandgap model file pardb/GaAs/BandStructure/Bandgap/Default.tcl calculates the model parameters represented by the Tcl variables Eg0, Chi0, alpha, beta, and Tpar and the material property bandgap represented by the Tcl variable Eq.

To plot the GaAs band gap as a function of temperature, specify the following code in the Inspect command file:

```
set ::material GaAs
set ::propertyGroup BandStructure
set ::parSection Bandgap
set ::propertyVariable Eg
```

Specifying physical variable name and parameter value

Many equation-based model files calculate the material property value as a function of the physical variables doping concentration, temperature, x-mole fraction, y-mole fraction, and wavelength of incident light.

The Material Parameter Plotter usually plots the material property on the y-axis and one of the physical variables on the x-axis. For equation-based models, the name of this physical variable is assigned to a Tcl variable xvar as follows:

```
set ::xvar <physicalVariable Name>
```

where physicalVariable_Name can be doping, temp, xMole, yMole, or lambda. If a model file calculates the physical property value as a function of more than one physical variable, the name of one of the physical variables is used to define xvar; whereas, the other physical variables are called parameters in this context. The value of the parameter is assigned to a Tcl variable named after the parameter as follows:

```
set ::<parameter Name> <parameter Value>
```

where parameter_Name can be any one of physicalVariable_Name, which is not assigned to xvar.

For example, for binaries, mobility depends on both doping concentration and temperature. In a command file that plots mobility as a function of doping concentration at a temperature of 300 K, the following commands are used:

```
set ::xvar doping
set ::temp 300
```

To plot mobility as a function of temperature for the doping concentration of 1×10^{18} cm⁻³, the following commands are used:

```
set ::xvar temp
set ::doping 1e18
```

For table-based models, the name of the physical variable is assigned to the Tcl variable XdataVar:

```
set ::XdataVar <physicalVariable Name>
```

These names are available in the corresponding model files. For example, the default GaAs TableBGN model calculates deltaEg n and deltaEg p as a function of Nd and Na.

To plot the donor doping concentration on the x-axis, use:

```
set ::XdataVar Nd
```

Creating list of the physical variable values

A list of values of the physical variable is created and stored in the Tcl variable <Xdata>. For equation-based models, this list can be generated using the procedures linspace, logspace, or decadelinspace (see Table 17 on page 69). The following command is used:

```
set <Xdata> [<function> <min> <max> <N>]
where function=<linspace | logspace | decadelinspace>.
```

The table-based models read a list of the physical variables and physical properties from data files and store these in separate lists. The procedure getXdataFromTable is used to read the list of physical variables and to store the values in <Xdata>:

```
set <Xdata> [getXdataFromTable]
```

Calculating list of material property values from model file

The list of values of the material property is computed from model files and is stored in a Tcl variable <Ydata> using the following command for equation-based models:

```
set <Ydata> [getDataFromEqn <Xdata>]
```

and using the following command for table-based models:

```
set <Ydata> [getYdataFromTable]
```

getDataFromEqn sources the model file, computes the list of the material property from the list of the physical variable, and returns the list of the computed material property. The path to the model file is built using the Tcl variables defined in Defining model and material property on page 77.

getYdataFromTable reads the material property values stored in the corresponding list in the model file and returns this list.

Creating and displaying curve in Inspect

The Inspect curve is created and displayed using the commands:

```
set curveName <curveName>
cv_createFromScript $curveName <Xdata> <Ydata>
cv_display $curveName
```

where <curveName> is the user-specified name of the curve.

Various properties of the plot such as curve attributes and axis attributes can be specified using appropriate Inspect commands [11].

Plotting and displaying multiple curves in Inspect

To plot and display multiple curves in a single instance of Inspect:

- 1. Plot a single curve as in Plotting and displaying a single curve in Inspect on page 76.
- 2. Modify the definition of Tcl variables defined in:
 - a) Defining model and material property on page 77
 - b) Specifying physical variable name and parameter value on page 78
 - c) Creating list of the physical variable values on page 79
- 3. Compute the list of the material property variable <Ydata>.
- 4. Create and display the curve in Inspect (see Creating and displaying curve in Inspect on page 79).

The above steps are illustrated by some examples from the Material Parameter Plotter example library. Following these steps, multiple curves created from:

- Equation-based models can be plotted together (see Plotting GaAs band gap (EgVsT)).
- Table-based models can be plotted together.
- Table-based and equation-based models can be plotted together (see Plotting n-GaAs bandgap narrowing (EbgnVsN) on page 82).

Example library

Table 20 lists the examples in the library of the Material Parameter Plotter. Each example is identified by the Inspect tool name, which is visible in each instance of the Inspect node.

Table 20 Examples in Material Parameter Plotter library

Inspect tool name	Description
EbgnVsN	Plots bandgap narrowing of n-GaAs as a function of doping concentration for table-based and equation-based models.
EgVsT	Plots band gap of GaAs as a function of temperature for multiple models.
EgVsxMole	Plots room temperature band gaps of AlGaAs as a function of xMole.

Table 20 Examples in Material Parameter Plotter library

Inspect tool name	Description
muVsNtemp	For a single model, plots electron mobility of GaAs as a function of doping concentration at different temperatures.
nkVslambda	For a single model, plots n and k of n-GaAs as a function of wavelength at different doping concentrations.

Plotting GaAs band gap (EgVsT)

The following listing plots the GaAs band gap as a function of temperature using the default model:

```
set ::material GaAs
set ::propertyGroup BandStructure
set ::parSection Bandgap
set ::model Default
set ::propertyVariable Eg
set ::xvar temp
set Xdata [linspace 0 300 50]
set Ydata [getDataFromEqn $Xdata]
set curveName $::model
cv_createFromScript $curveName $Xdata1 $Ydata1
cv display $curveName
```

To plot an additional curve for the temperature variation of GaAs band gap using the Levinshtein-RT model, only the model name is redefined, followed by commands for computing the list of the material property variable, creating the curve, and plotting the curve:

```
set ::model Levinshtein-RT
set Ydata1 [getDataFromEqn $Xdata]
set curveName $::model
cv_createFromScript $curveName $Xdata $Ydata1
cv_display $curveName
```

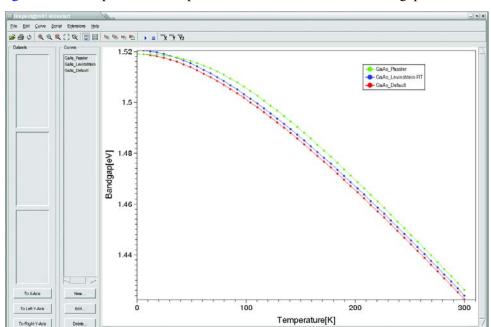


Figure 6 shows a plot of the temperature variation of the GaAs band gap for different models.

Figure 6 Plot of GaAs band gap as a function of temperature for multiple models

Plotting n-GaAs bandgap narrowing (EbgnVsN)

The following listing plots n-GaAs bandgap narrowing as a function of donor concentration using the table-based Jain–Roulston default model:

```
set ::material GaAs
set ::propertyGroup BandStructure
set ::parSection TableBGN
set ::model JainRoulston-Default
set ::propertyVariable deltaEg_n
set ::XdataVar Nd
set Xdata [getXdataFromTable]
set Ydata [getYdataFromTable]
set curveName $::model
cv_createFromScript $curveName $Xdata $Ydata
cv display $curveName
```

The following listing plots an additional curve for the table-based Schubert model:

```
set ::model Schubert
set Xdata [getXdataFromTable]
set Ydata [getYdataFromTable]
set curveName $::model
```

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```
cv_createFromScript $curveName $Xdata $Ydata
cv_display $curveName
```

The following listing plots an additional curve for the equation-based Blieske model:

```
set ::model Blieske
set ::propertyVariable deltaEg
set ::xvar doping
set Xdata [decadelinspace 1e15 1e20 10]
set Ydata [getDataFromEqn $Xdata]
set curveName $::model
cv_createFromScript $curveName $Xdata $Ydata
cv display $curveName
```

References

- [1] Y. P. Varshni, "Temperature Dependence of the Energy Gap in Semiconductors," *Physica*, vol. 34, no. 1, pp. 149–154, 1967.
- [2] Sentaurus Device User Guide, Version A-2007.12, Mountain View, California: Synopsys, Inc., 2007.
- [3] B. B. Welch, K. Jones, and J. Hobbs, *Practical Programming in Tcl and Tk*, Upper Saddle River, New Jersey: Prentice Hall PTR, 4th ed., 2003.
- [4] *Sentaurus Workbench User Guide*, Version A-2007.12, Mountain View, California: Synopsys, Inc., 2007.
- [5] P. Lautenschlager *et al.*, "Interband critical points of GaAs and their temperature dependence," *Physical Review B*, vol. 35, no. 17, pp. 9174–9189, 1987.
- [6] R. Pässler, "Parameter Sets Due to Fittings of the Temperature Dependencies of Fundamental Bandgaps in Semiconductors," *Physica Status Solidi* (b), vol. 216, no. 2, pp. 975–1007, 1999.
- [7] V. V. Mitin, V. A. Kochelap, and M. A. Stroscio, *Quantum Heterostructures: Microelectronics and Optoelectronics*, Cambridge: Cambridge University Press, 1999.
- [8] M. Levinshtein, S. Rumyantsev, and M. Shur, *Handbook Series on Semiconductor Parameters, Si, Ge, C (Diamond), GaAs, GaP, GaSb, InAs, InP, InSb*, vol. 1, Singapore: World Scientific, 1996.
- [9] J. Piprek, Semiconductor Optoelectronic Devices: Introduction to Physics and Simulation, Amsterdam: Academic Press, 2003.

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References

- [10] G. P. Donati, R. Kaspi, and K. J. Malloy, "Interpolating semiconductor alloy parameters: Application to quaternary III–V band gaps," *Journal of Applied Physics*, vol. 94, pp. 5814–5819, November 2003.
- [11] *Inspect User Guide*, Version A-2007.12, Mountain View, California: Synopsys, Inc., 2007.

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CHAPTER 5

Creating applications using template directory

This chapter describes how to create applications with the template directory.

Overview

In general, the applications that use Epi and MatPar reside in the Meta project (<MetaProject>) directory, which contains the epi Sentaurus Workbench project and the subdirectories lib, par, and pardb.

It also contains multiple Sentaurus Workbench custom projects (<CustomProject>). The custom projects are created by copying and renaming the Sentaurus Workbench project.

There can be any number of custom projects in a <MetaProject> directory. Usually, a <MetaProject> corresponds to a particular device, and the custom projects correspond to various Sentaurus Workbench projects for the device. In addition, there can be multiple <MetaProject> directories in \$STDB. For a given <MetaProject>, there is a common lib, par, and pardb subdirectory.

Creating a Meta project

To use the Epi/MatPar template directory to create a Meta project and custom projects:

- 1. Download and unpack the Epi/MatPar template directory epi_template.gzp using the download instructions in the application note *Template for Creating and Simulating Multilayered Heterostructure Devices with TCAD Sentaurus* [1].
- 2. Uncompress and untar epi_template.tar.gz in any directory under \$STDB.
 - The resulting directory structure is shown in Table 1 on page 1.
- 3. Create a <MetaProject > folder:
 - a) Copy and paste the epi template folder into any directory under \$STDB.
 - b) Rename the folder.

- 4. To create a single Sentaurus Workbench custom project:
 - a) Copy and paste the epi Sentaurus Workbench project into the <MetaProject> directory.
 - b) Rename the project.
 - c) Similarly, you can create multiple Sentaurus Workbench custom projects under a single <MetaProject> directory:
- 5. Select model names for each property and material by consulting the documentation of the Material Parameter Database (see Material Parameter Database on page 41).
 - To create new model files, see Adding new models and new materials on page 43 and Model files on page 58.
- 6. Prepare the source parameter files to be used for creating user-defined regionwise or materialwise parameter files. There can be one <material>.par and one <material>.tcl file for each material or region. These source parameter files are used for all the custom projects:
 - a) The template Tcl source parameter file can be used to create the <material>.tcl file for each material: Specify the material name, the cbo value in the case of heterostructures, the commands in the Input Validation and Header Printing section, and one initProperty and print statement for each section to be printed. Specify the model names in the initProperty statements. See Source parameter files on page 52 and Template Tcl source parameter file on page 58.
 - b) The <material > .par files can be created by either using the default parameter files or changing the model parameters in the default parameter files (see Source parameter files on page 52).

For a particular custom project:

- 1. Specify the following information in the Epi command file epi_epi.csv (see Chapter 2 on page 7):
 - a) Description of the multilayer stack.
 - b) Description of each layer.
 - c) Global mesh refinement strategy.
 - d) Regionwise mesh refinement strategy in the y-direction.
 - e) Source parameter files.
 - f) Extension column content to be inserted in preprocessed Sentaurus Device command file.
- 2. Verify the multilayer stack created by Epi using Tecplot SV. The structure is stored in n@node@ epi msh.tdr.

- 3. Add the following Scheme commands in the command file (sde_dvs.cmd) of the subsequent Sentaurus Structure Editor node (see Chapter 3 on page 35):
 - a) Load the Scheme script file n@node@ epi.scm generated by Epi.
 - b) Perform further device processing.
 - c) Add contacts.
 - d) Define the mesh refinement strategy in the y-direction and z-direction (only for 3D).
 - e) Invoke the mesher.
- 4. Edit the MatPar command file MatPar_mpr.cmd, specifying (see MatPar command file on page 45):
 - a) Device temperature.
 - b) Wavelength of incident light if required.
 - c) Reference material for heterostructures.
 - d) Name of the main parameter file.
 - e) Location of the Material Parameter Database.
 - f) Commands for inserting extension columns in preprocessed Sentaurus Device command file.
- 5. Add the required tools after the MatPar node in the tool row, and edit the command files of these tools.

The simulation project for the application note *Simulation of 2D Single-junction AlGaAs/GaAs Solar Cells with Transfer Matrix Method* [2] has been created using the above procedure.

References

- [1] Template for Creating and Simulating Multilayered Heterostructure Devices with TCAD Sentaurus, TCAD Sentaurus application note, available from SolvNet at https://solvnet.synopsys.com, April 2008.
- [2] Simulation of 2D Single-junction AlGaAs/GaAs Solar Cells with Transfer Matrix Method, TCAD Sentaurus application note, available from SolvNet at https://solvnet.synopsys.com, April 2008.

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